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(54) **SEMICONDUCTOR DEVICE WITH AN INTERCONNECT ELEMENT AND METHOD FOR MANUFACTURE**

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H01L 21/768 (2006.01)

(52) **U.S. Cl.** **257/621; 257/737; 257/E23.011**

(58) **Field of Classification Search** **257/621, 257/737, E23.011**

See application file for complete search history.

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(57) **ABSTRACT**

A semiconductor device is provided configured to be electrically connected to another device by through silicon interconnect technology. The semiconductor device includes a semiconductor substrate with at least one through hole. A through silicon conductor extends inside the through hole from the upper side to the bottom side of the semiconductor substrate. The through silicon conductor is electrical isolated from the semiconductor substrate and includes a conductor bump at one of its ends. Between the inner surface of the through hole and the through silicon conductor a gap is formed. The gap surrounds the through silicon conductor on one side of the semiconductor substrate having the conductor bump, and extends from this side of the substrate into the substrate. The gap is filled with a flexible dielectric material.

7 Claims, 7 Drawing Sheets

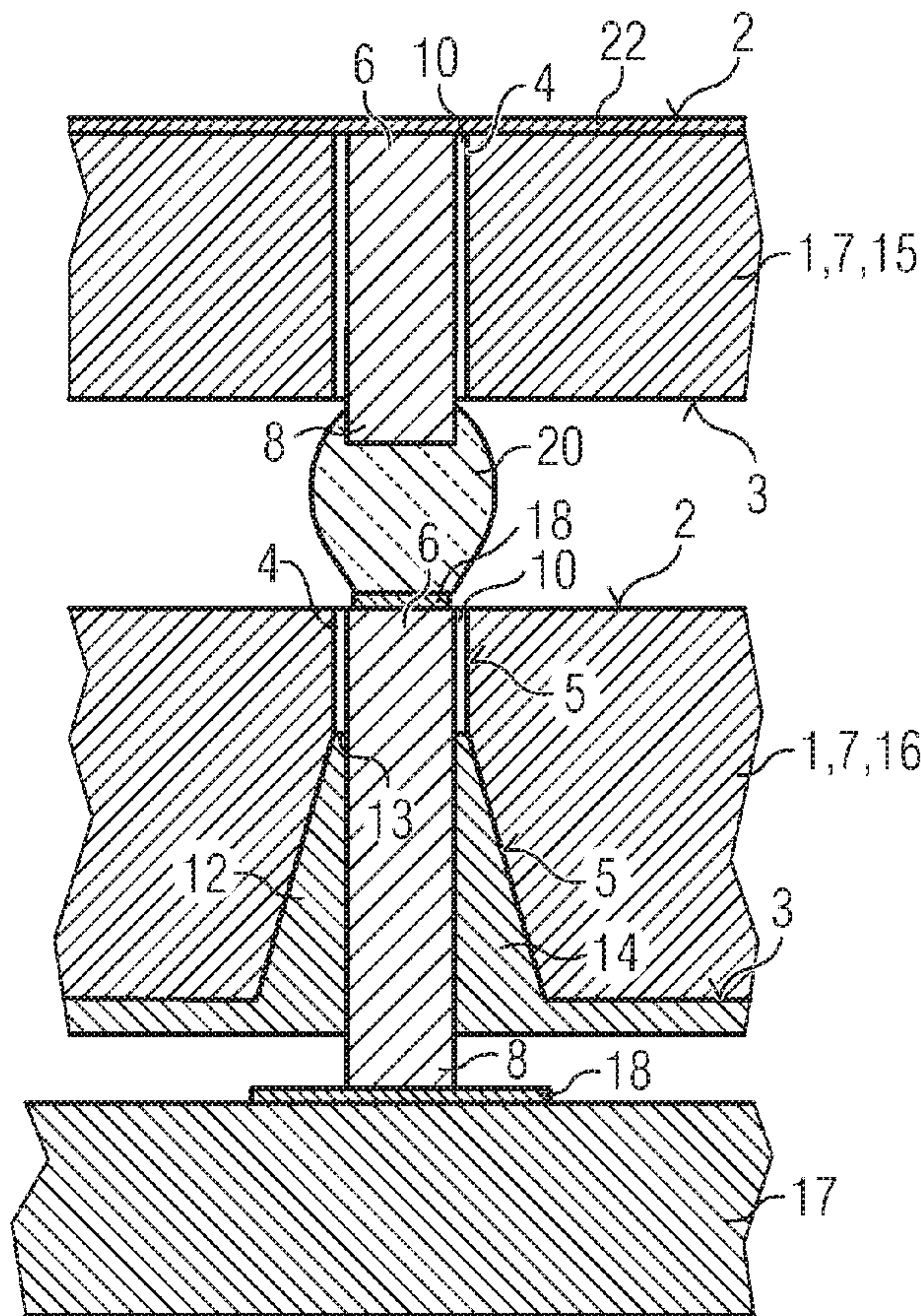


FIG 1

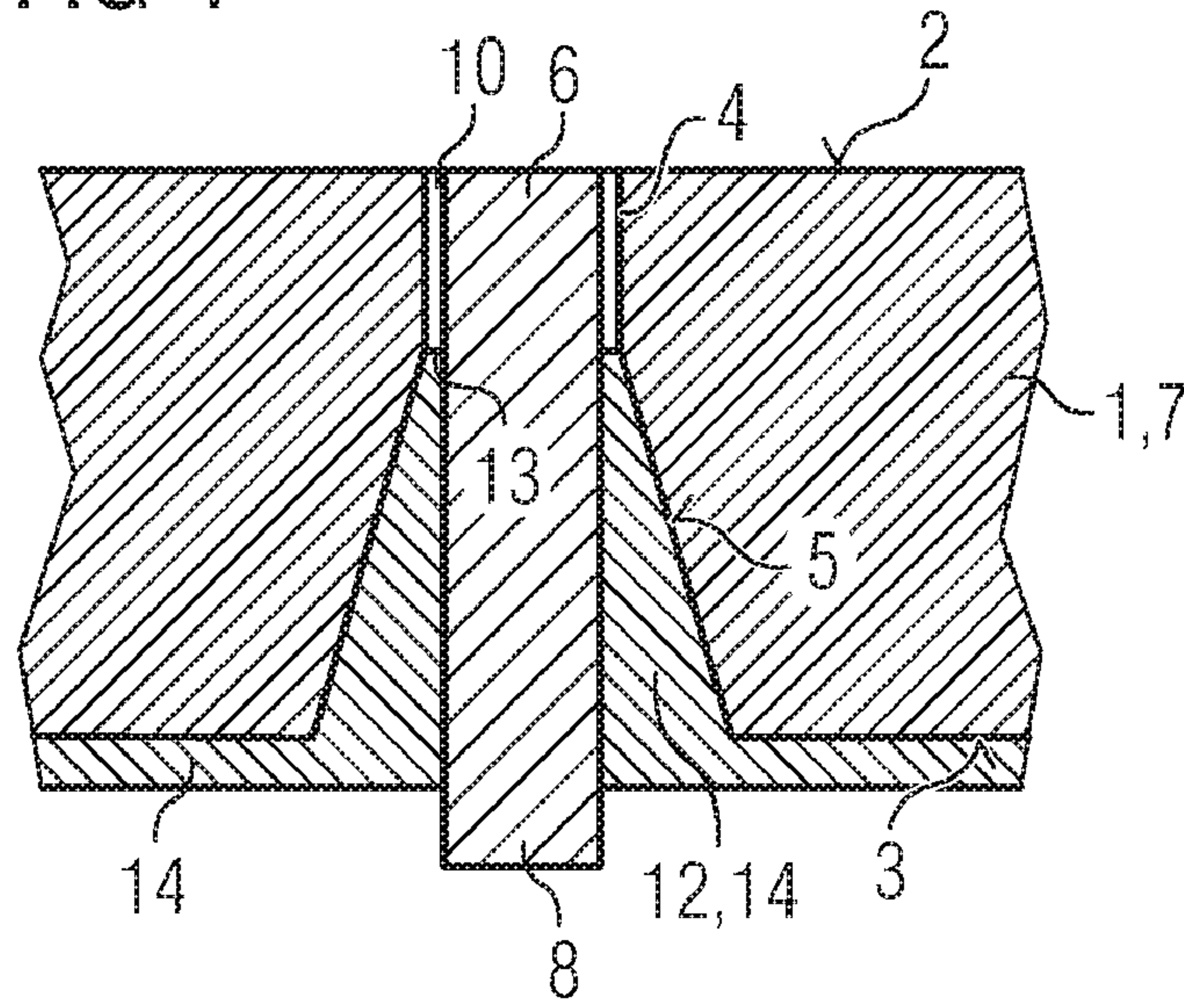


FIG 2

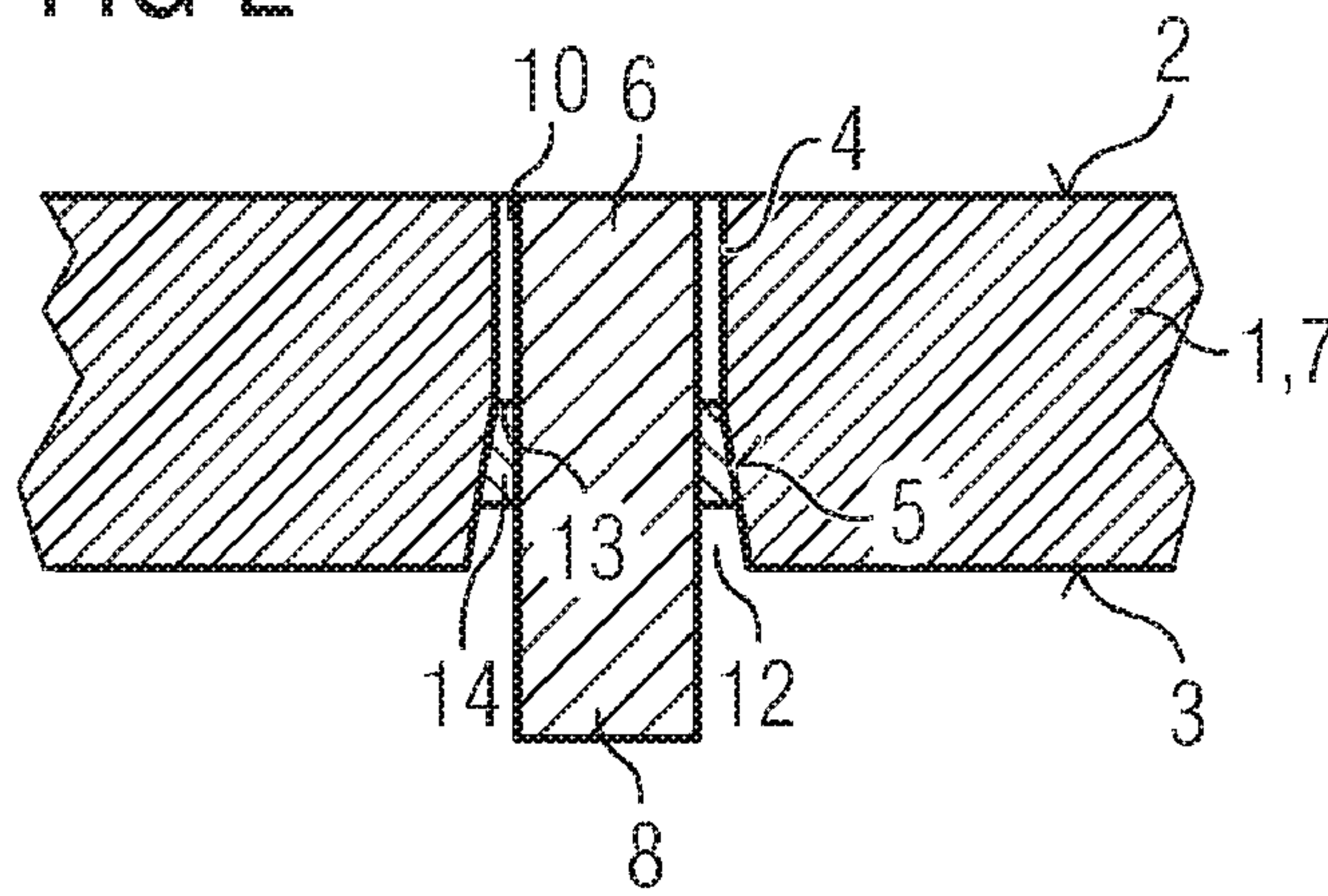


FIG 3

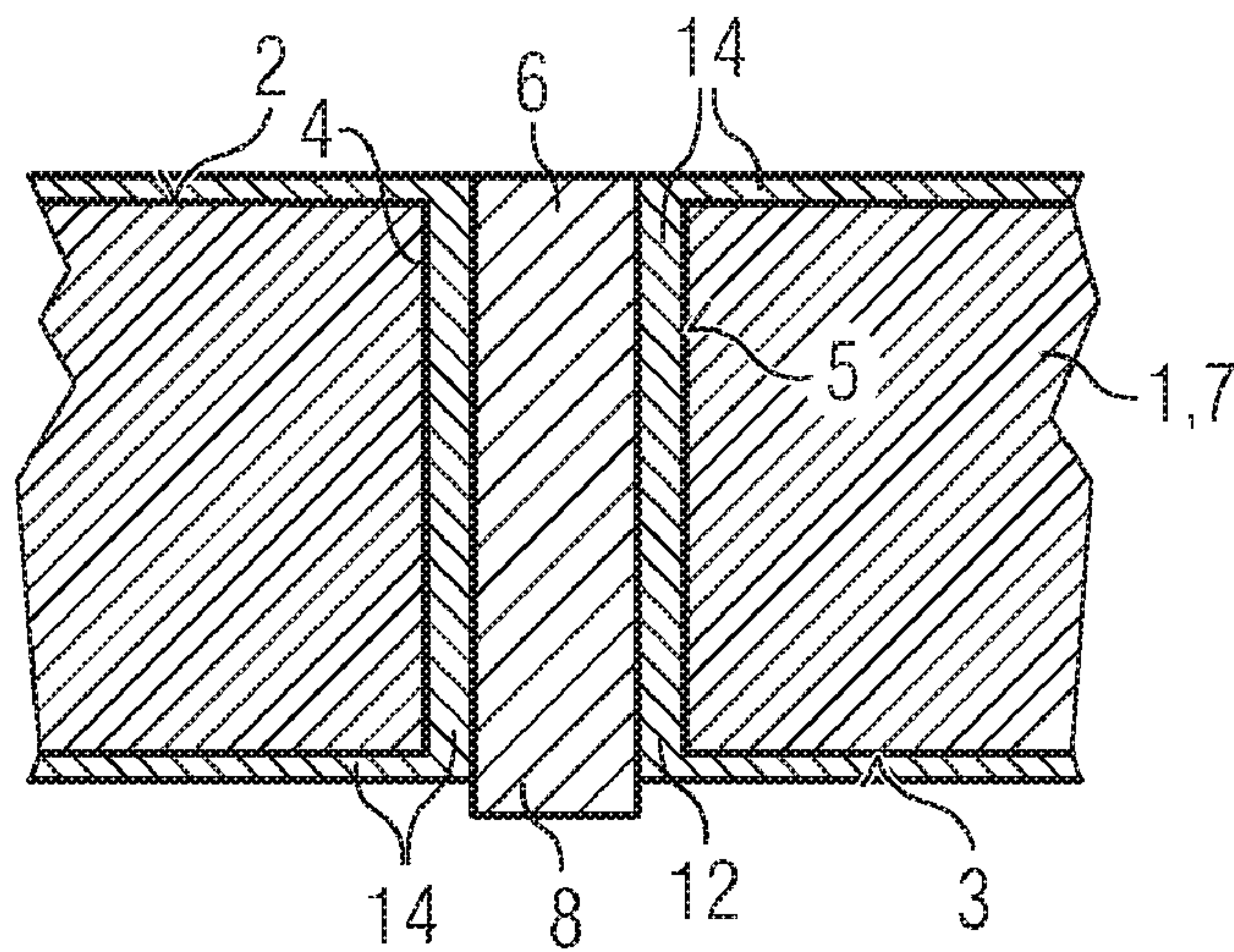


FIG 4

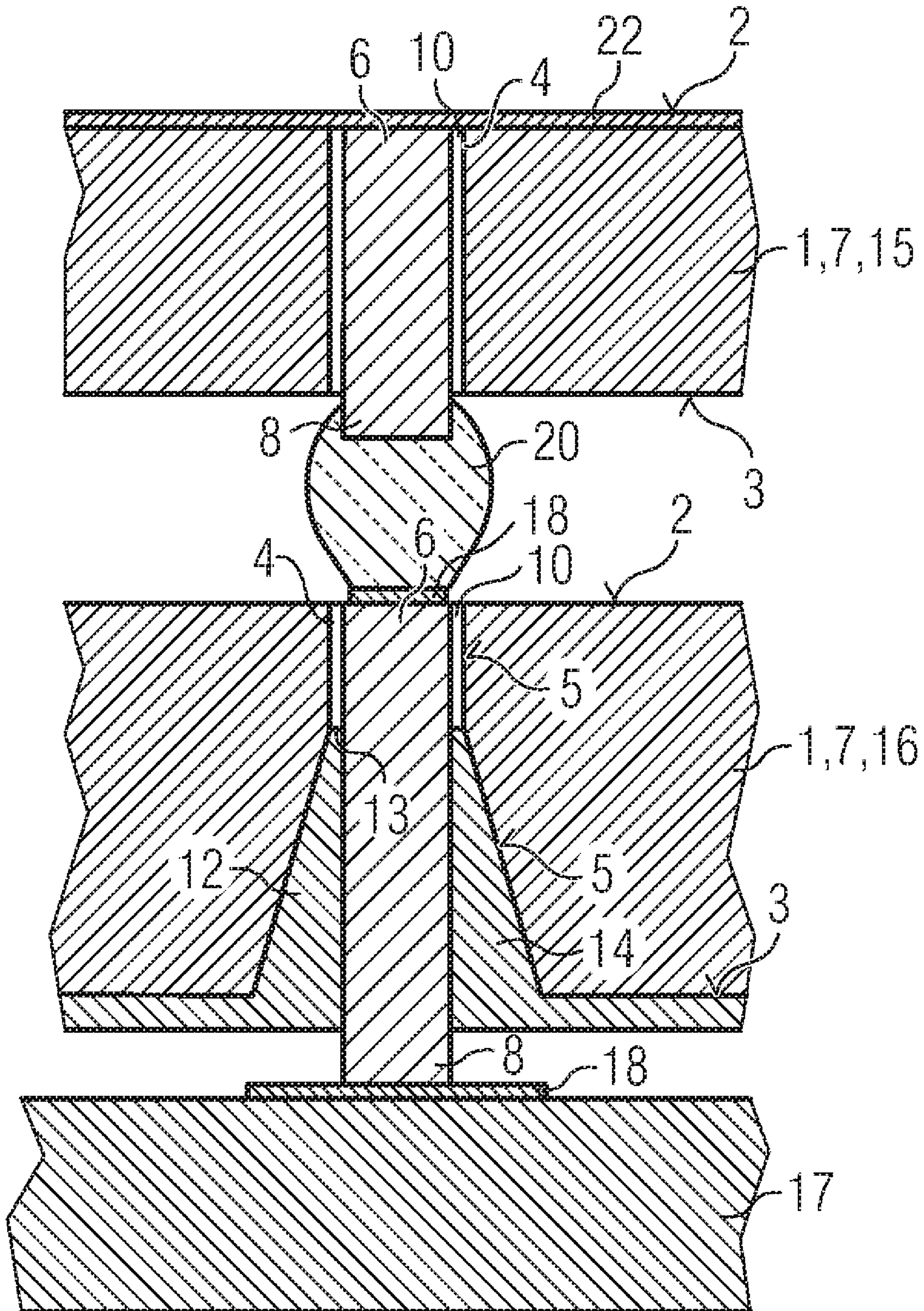


FIG 5A

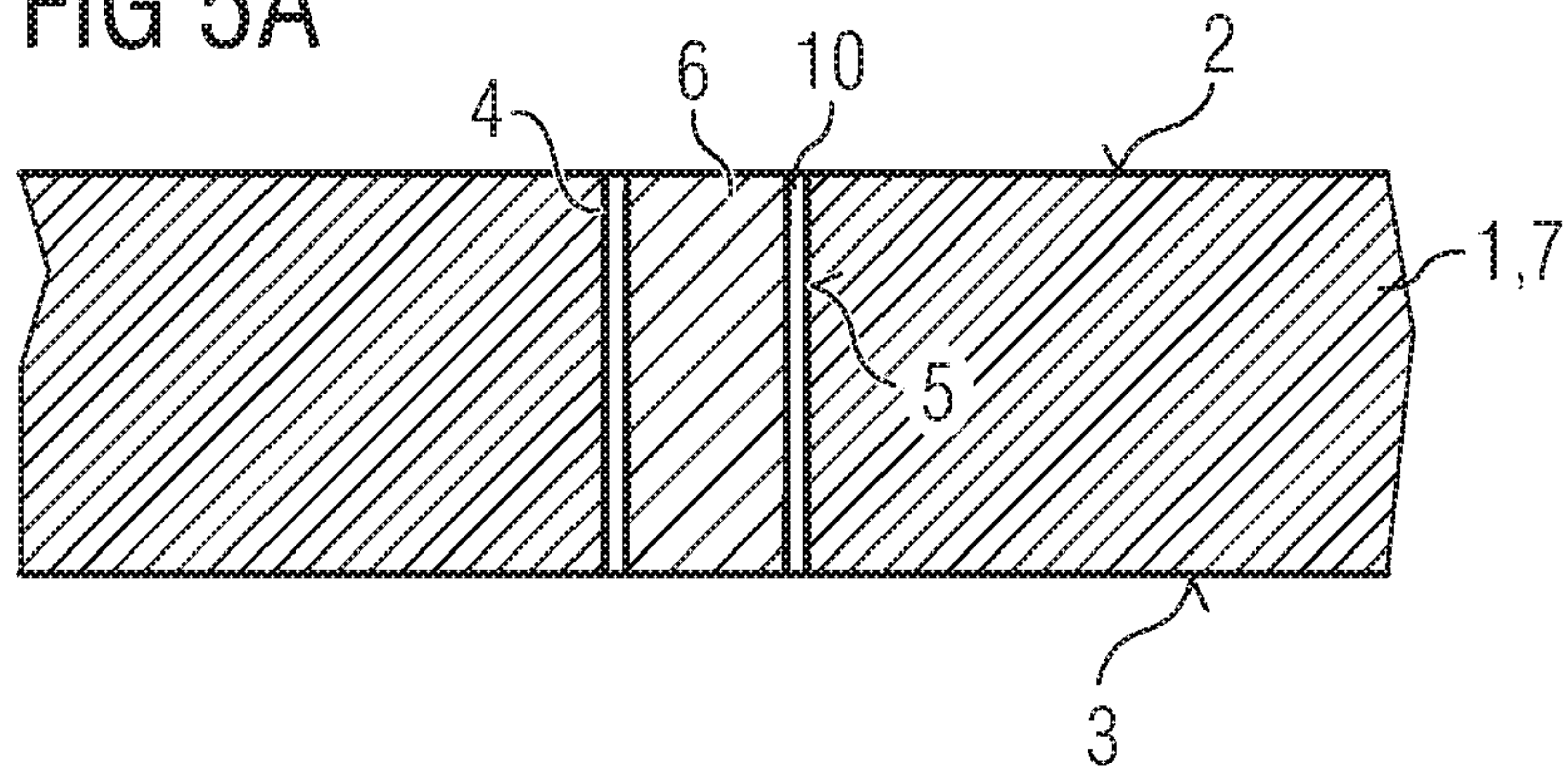


FIG 5B

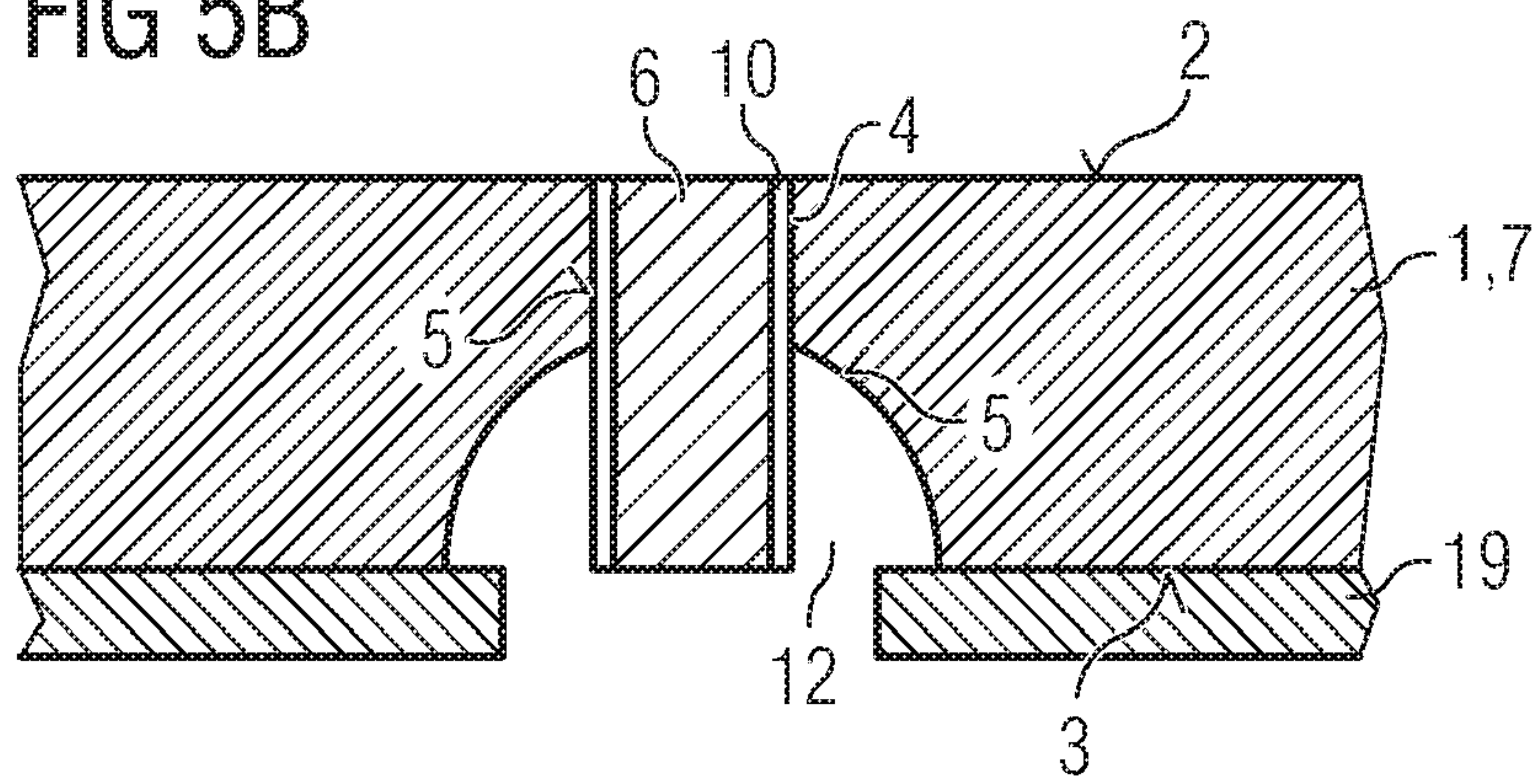


FIG 5C

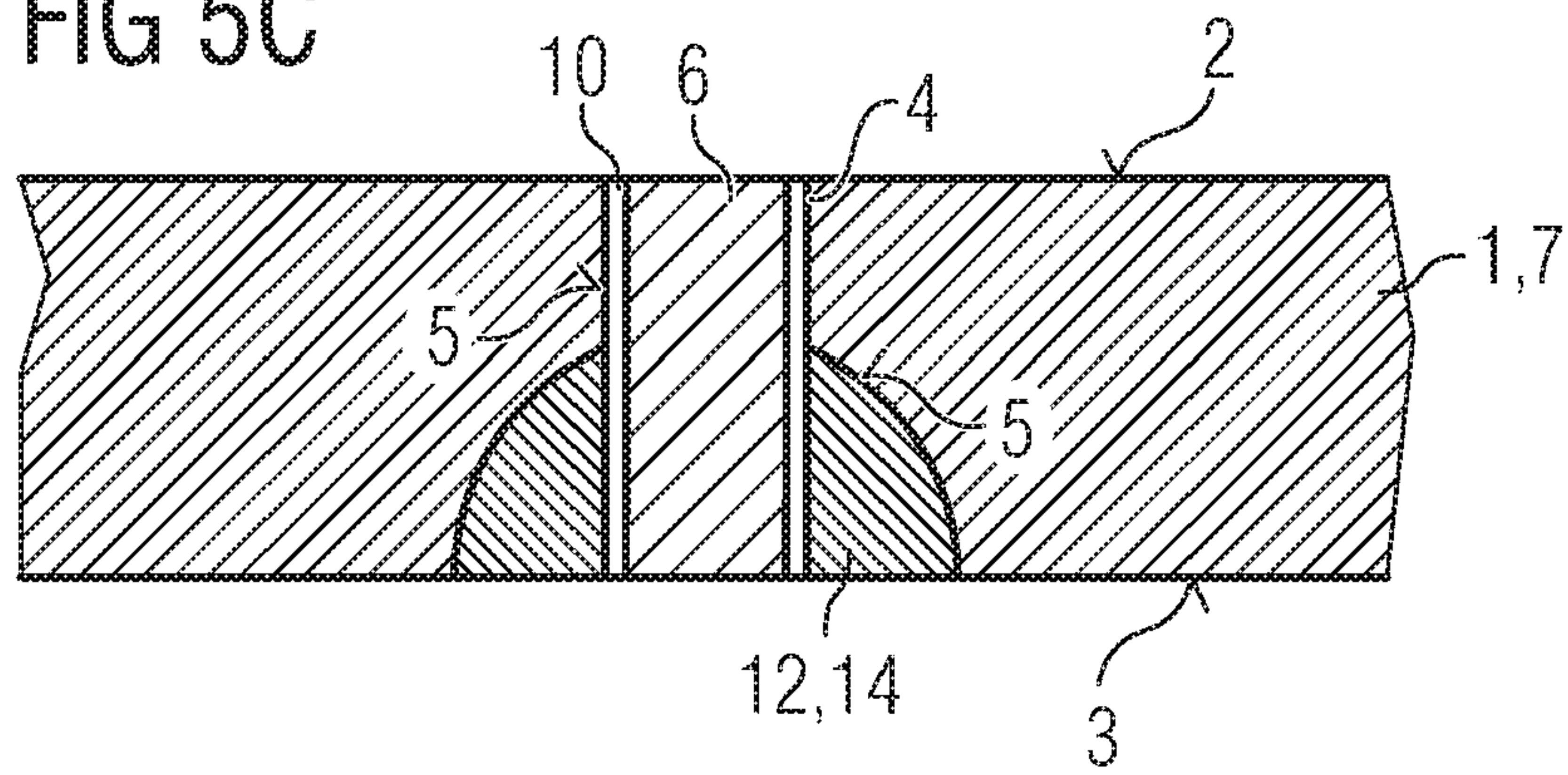


FIG 5D

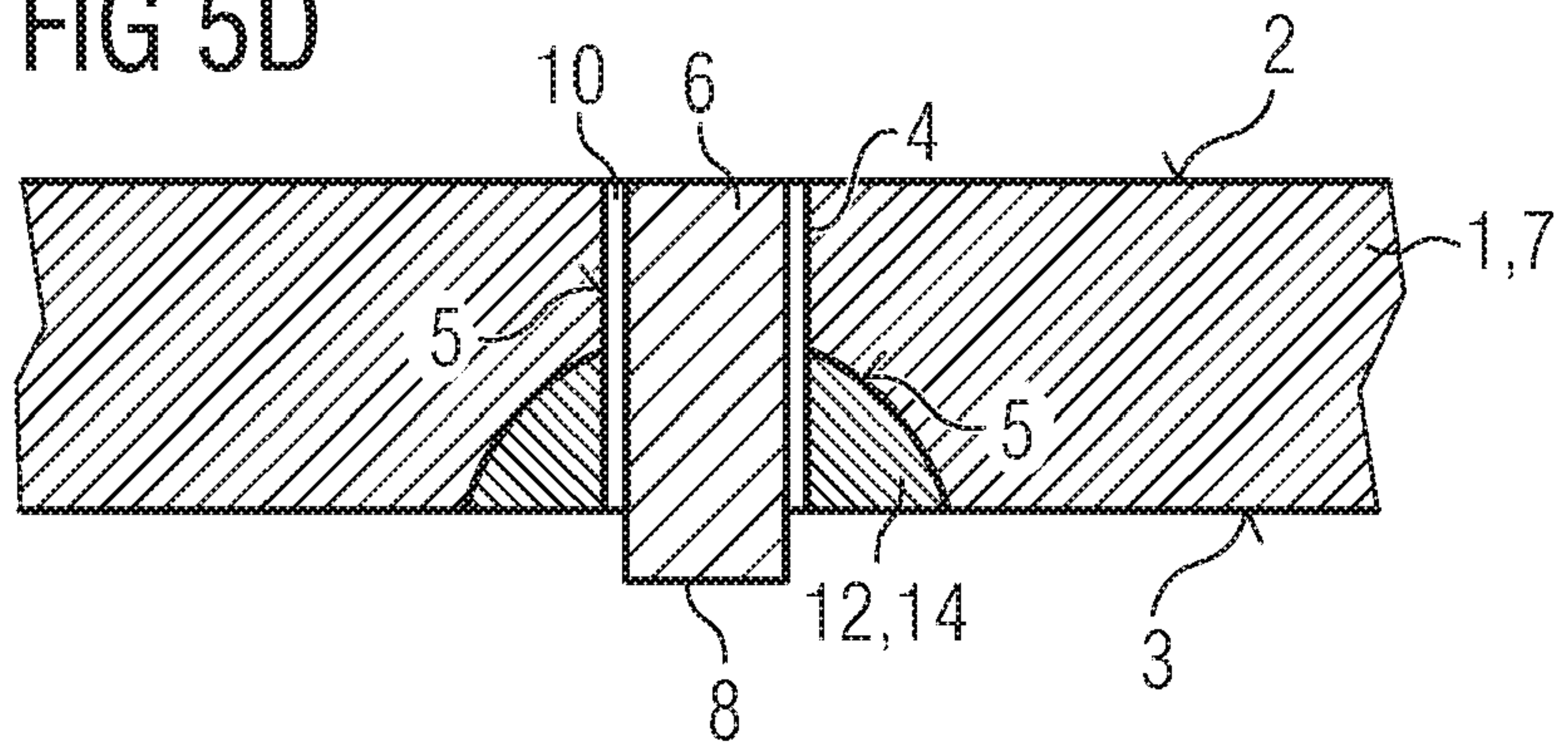


FIG 6A

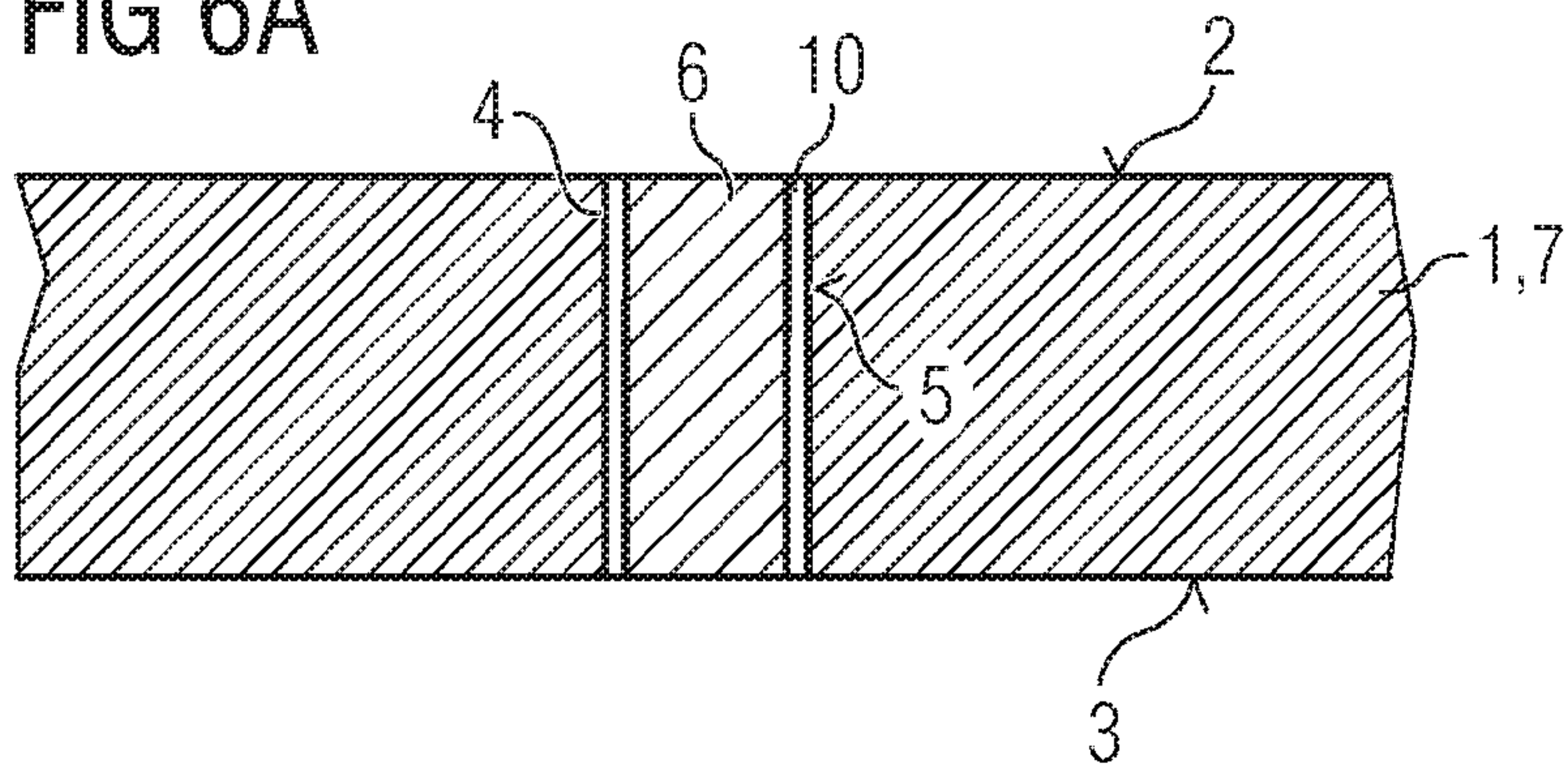


FIG 6B

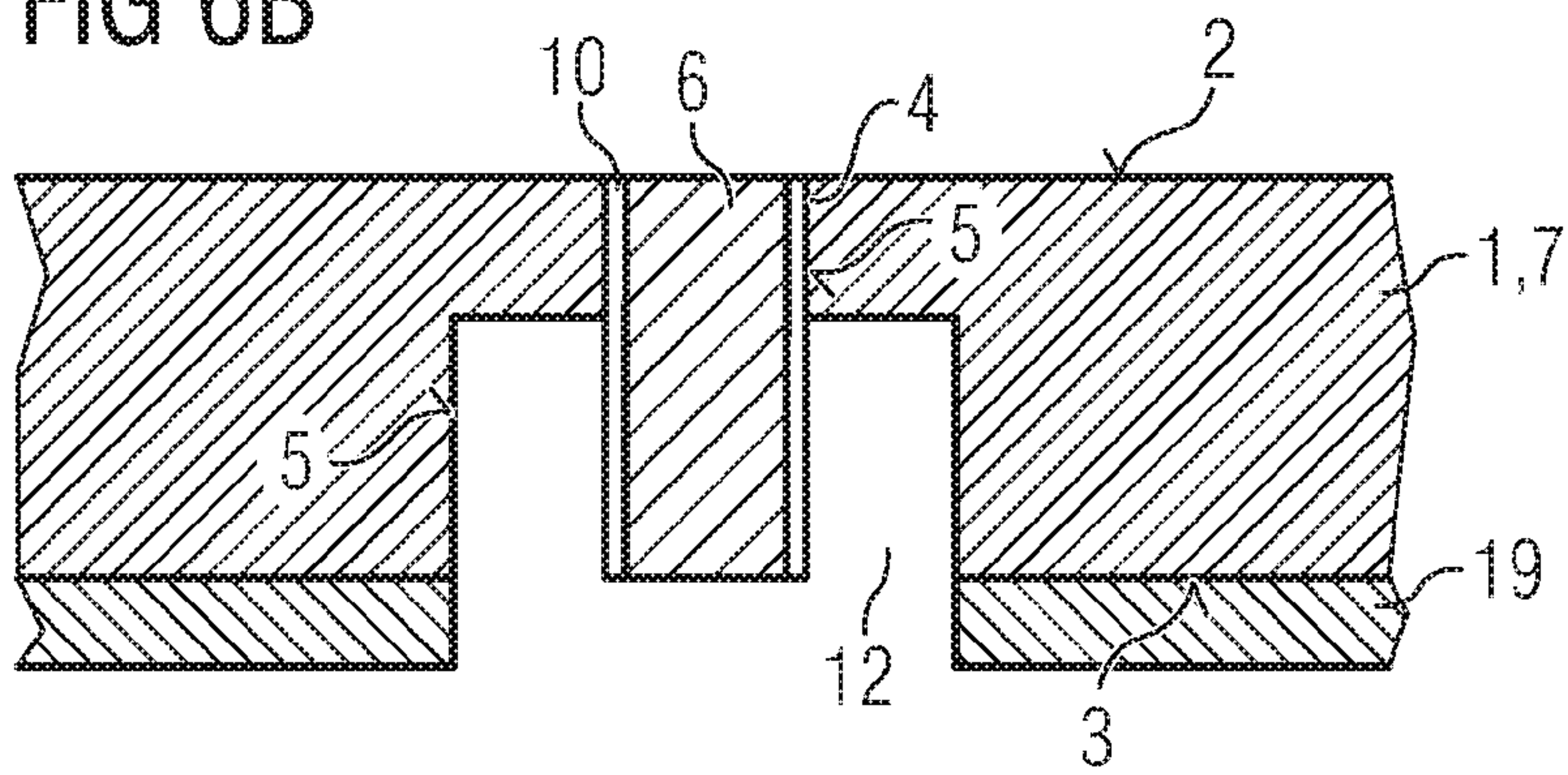


FIG 6C

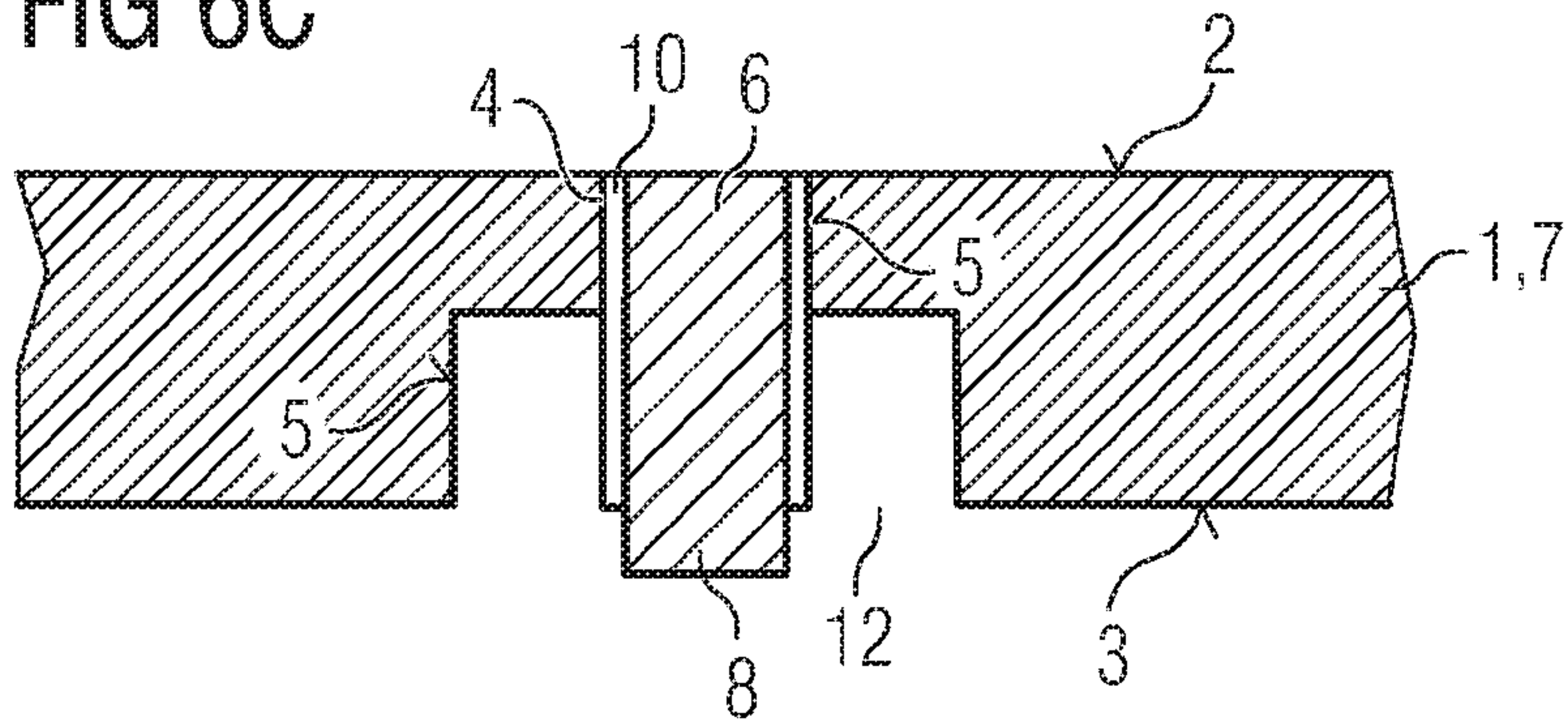


FIG 6D

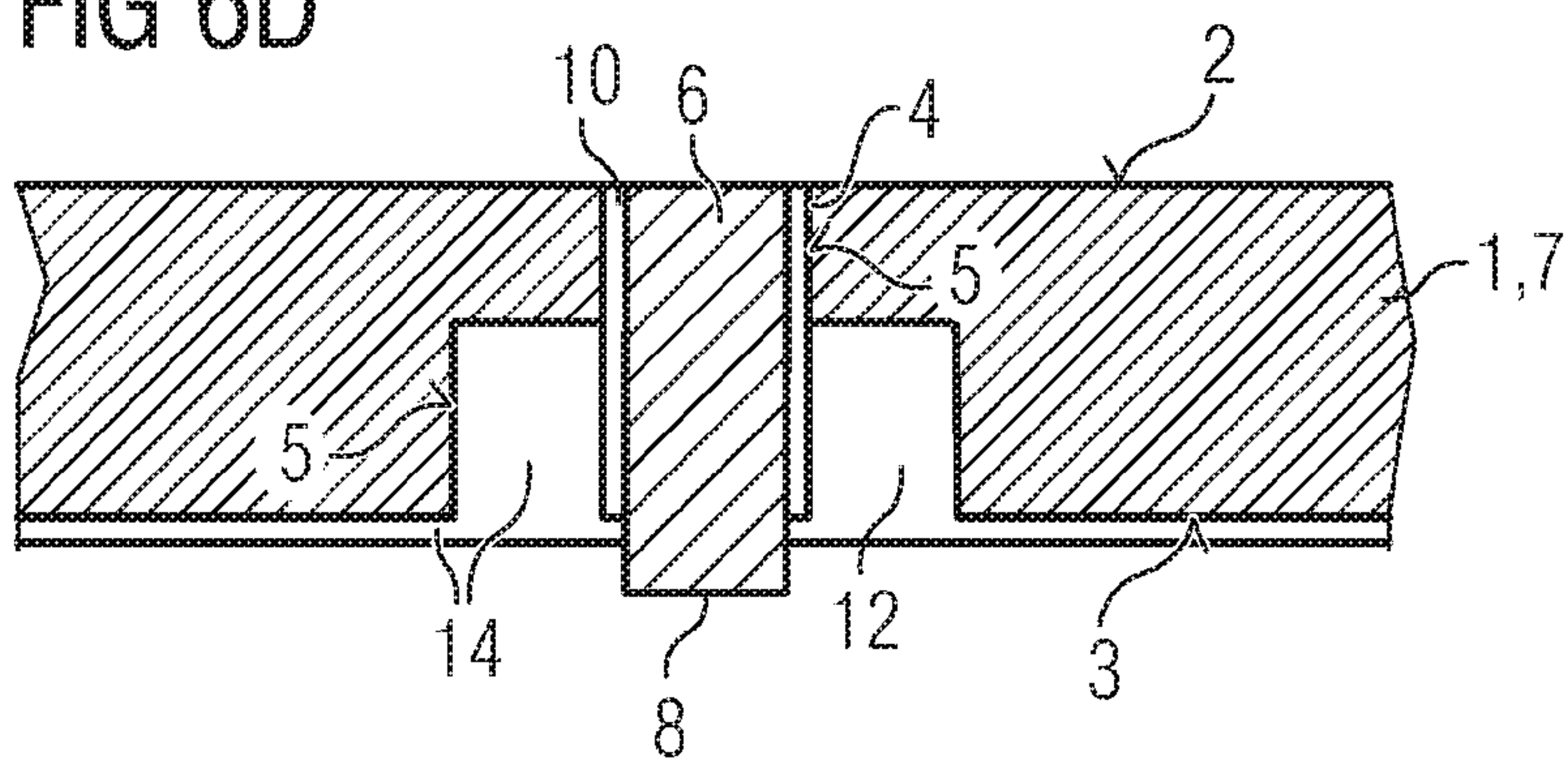


FIG 7A

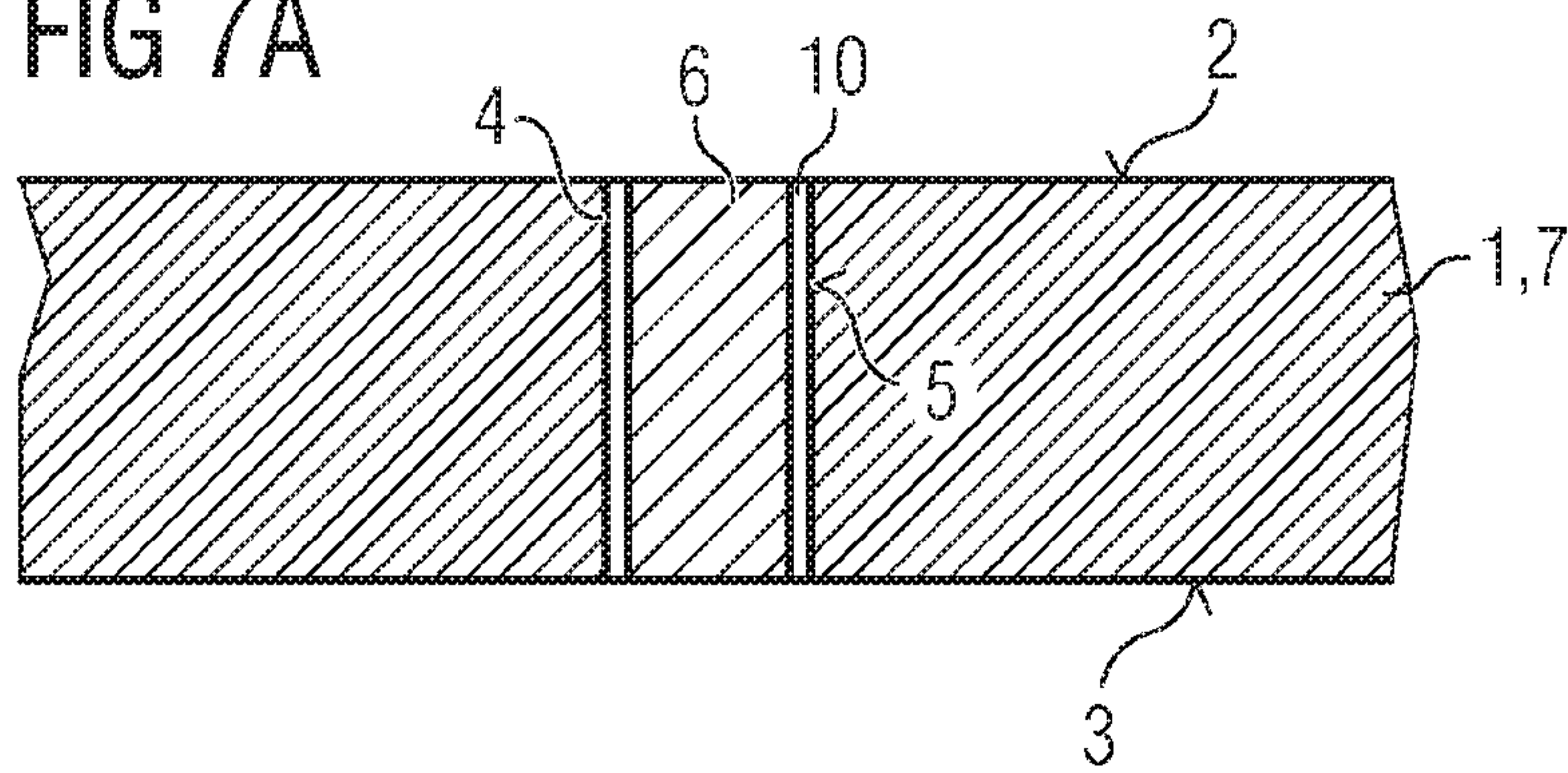


FIG 7B

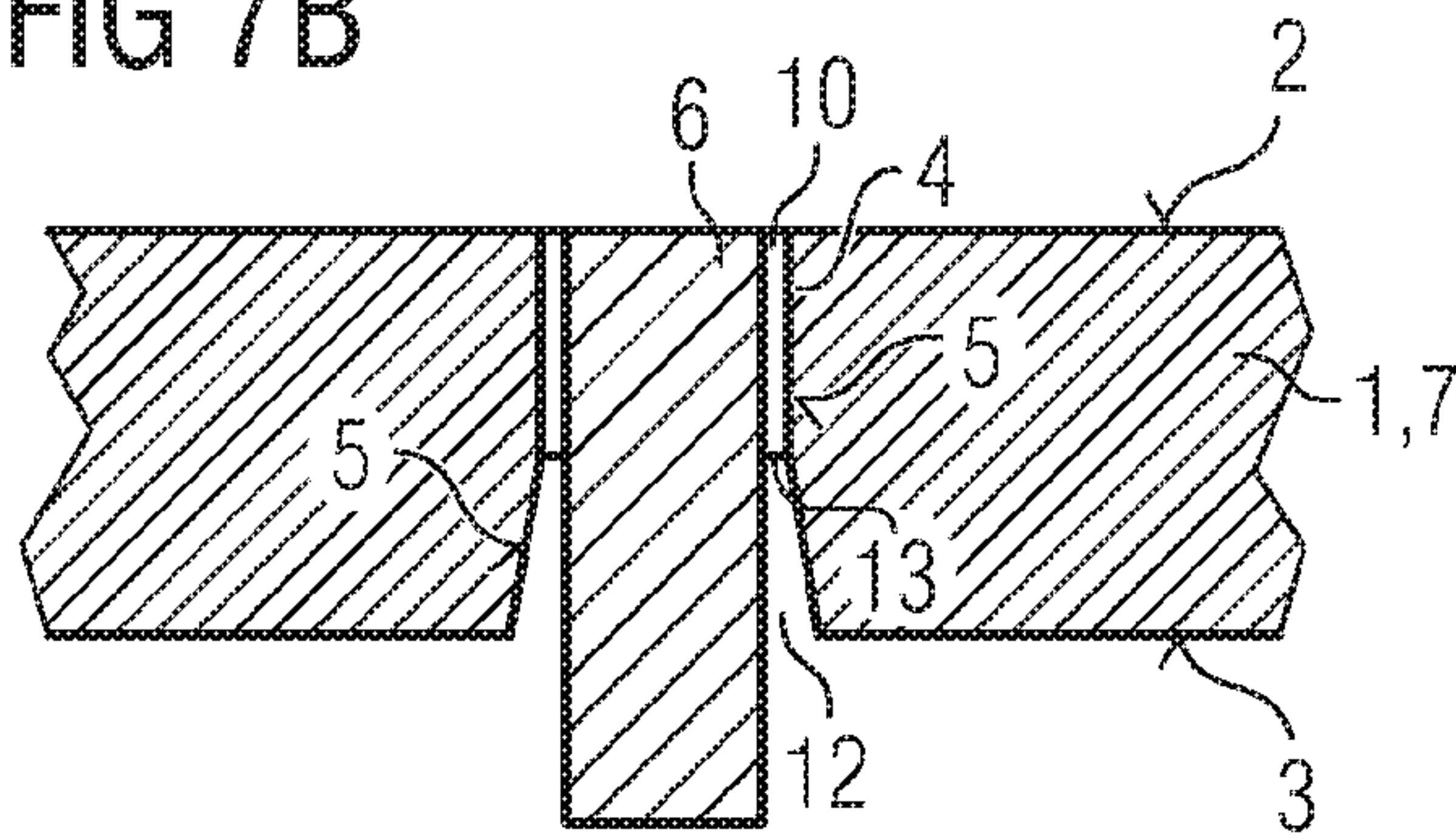


FIG 7C

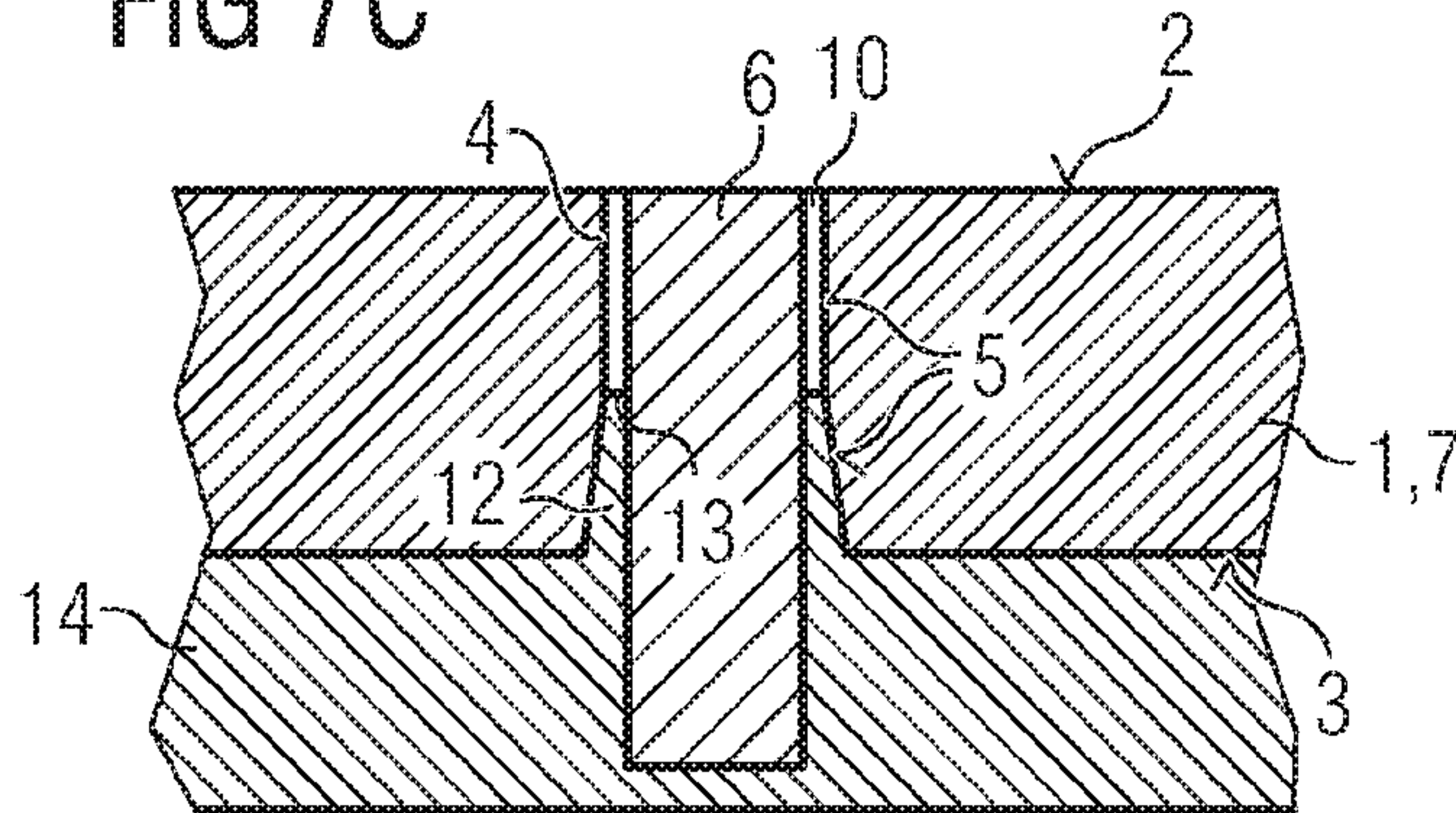


FIG 7D

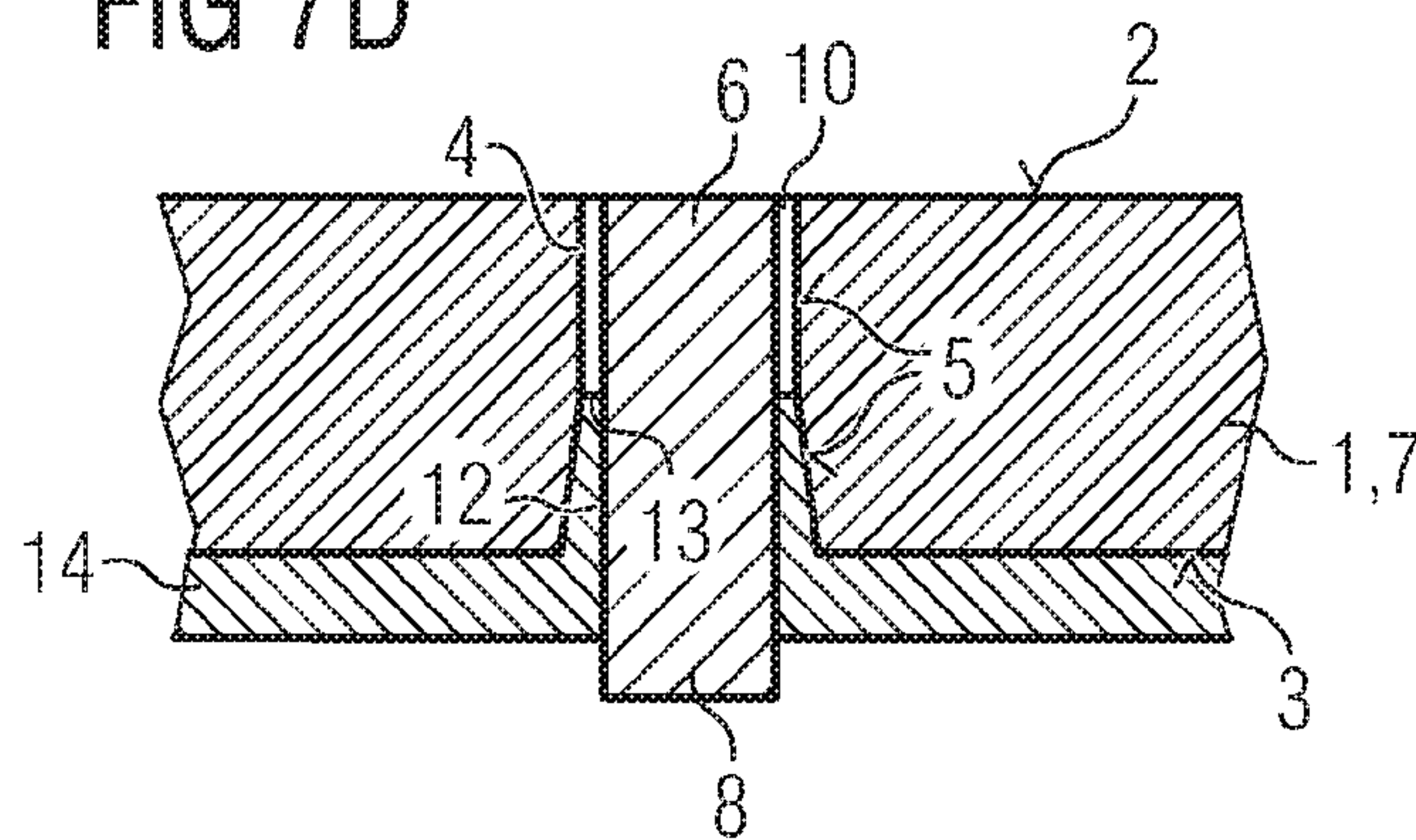


FIG 8A

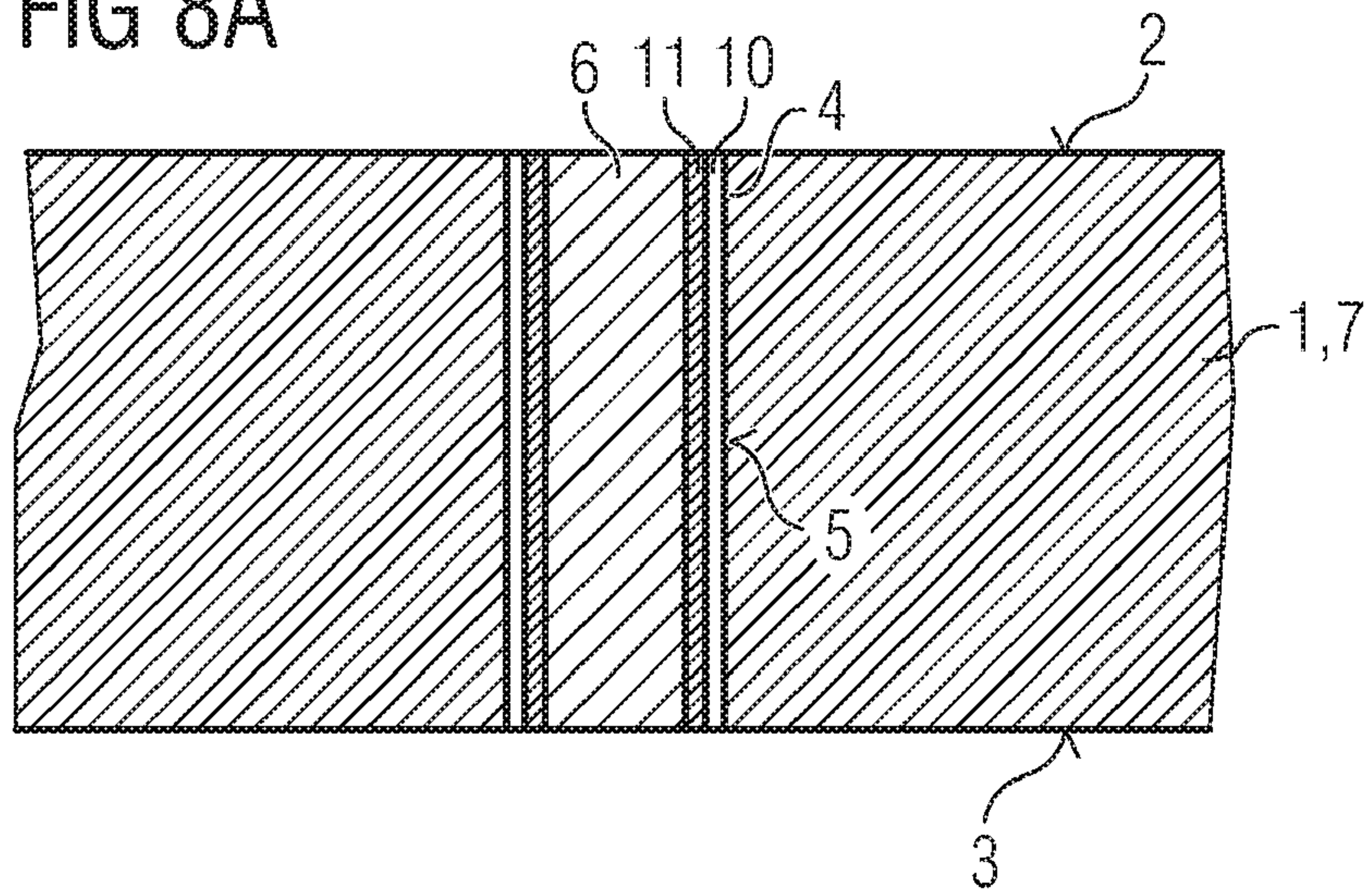


FIG 8B

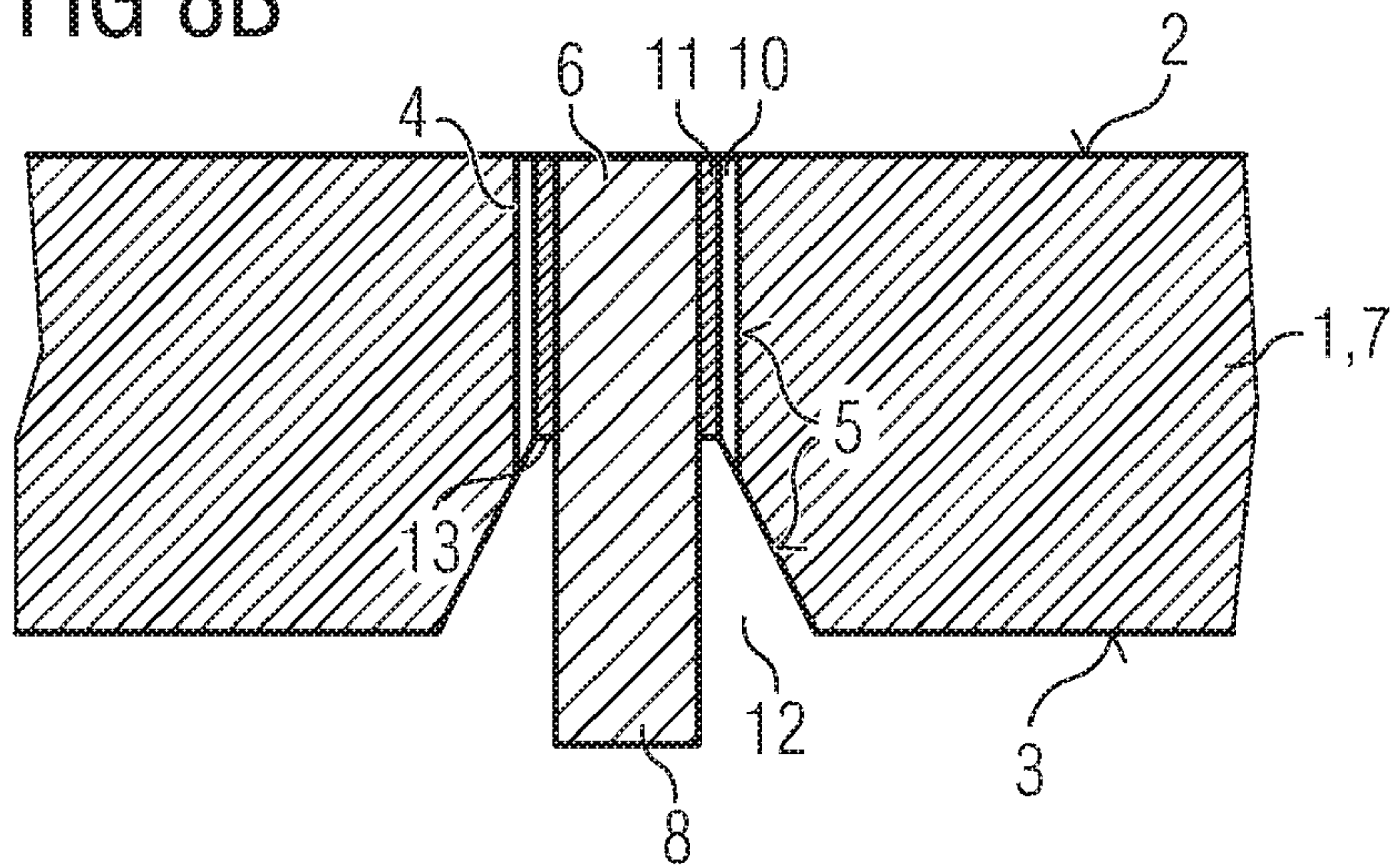


FIG 8C

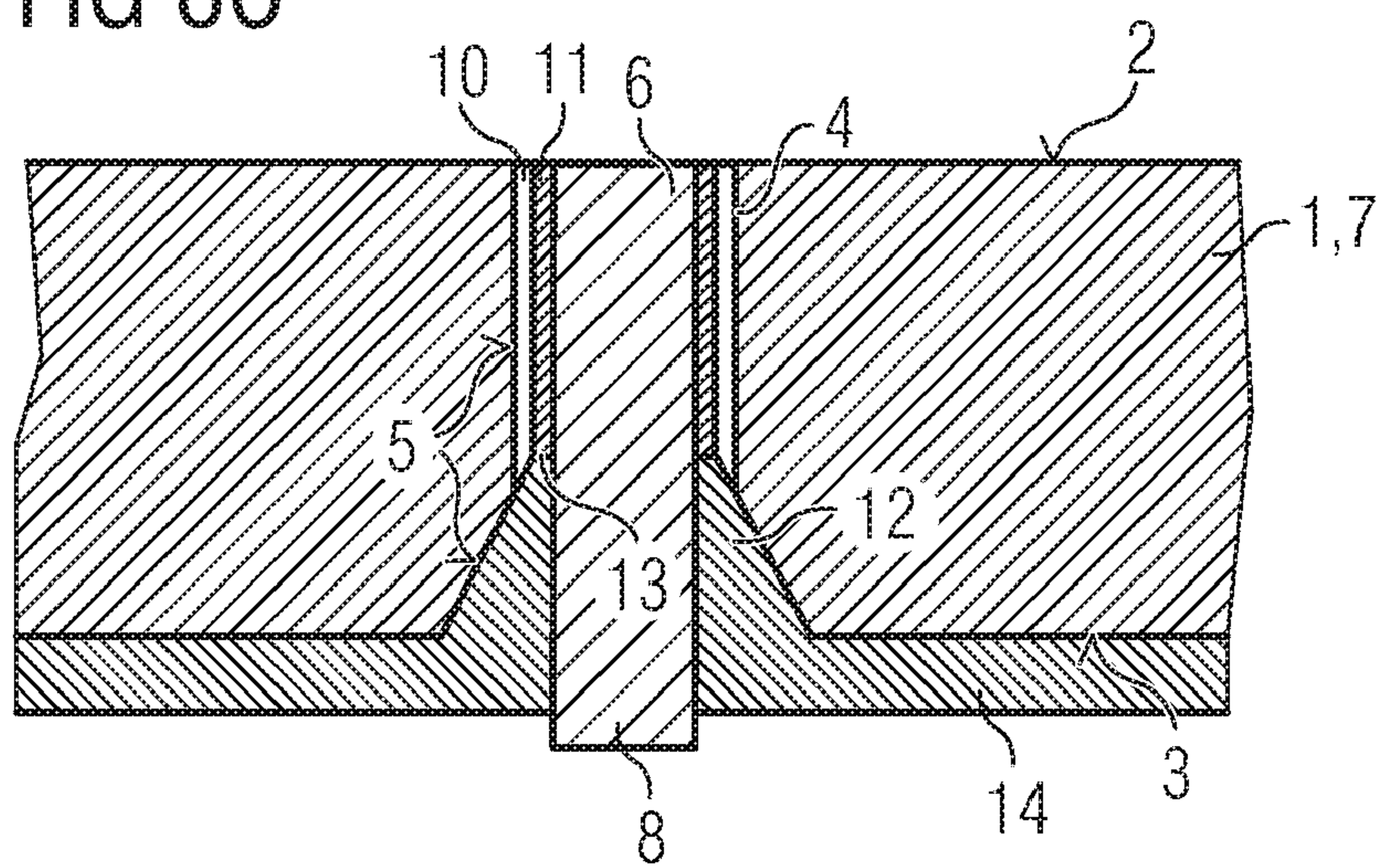


FIG 9A

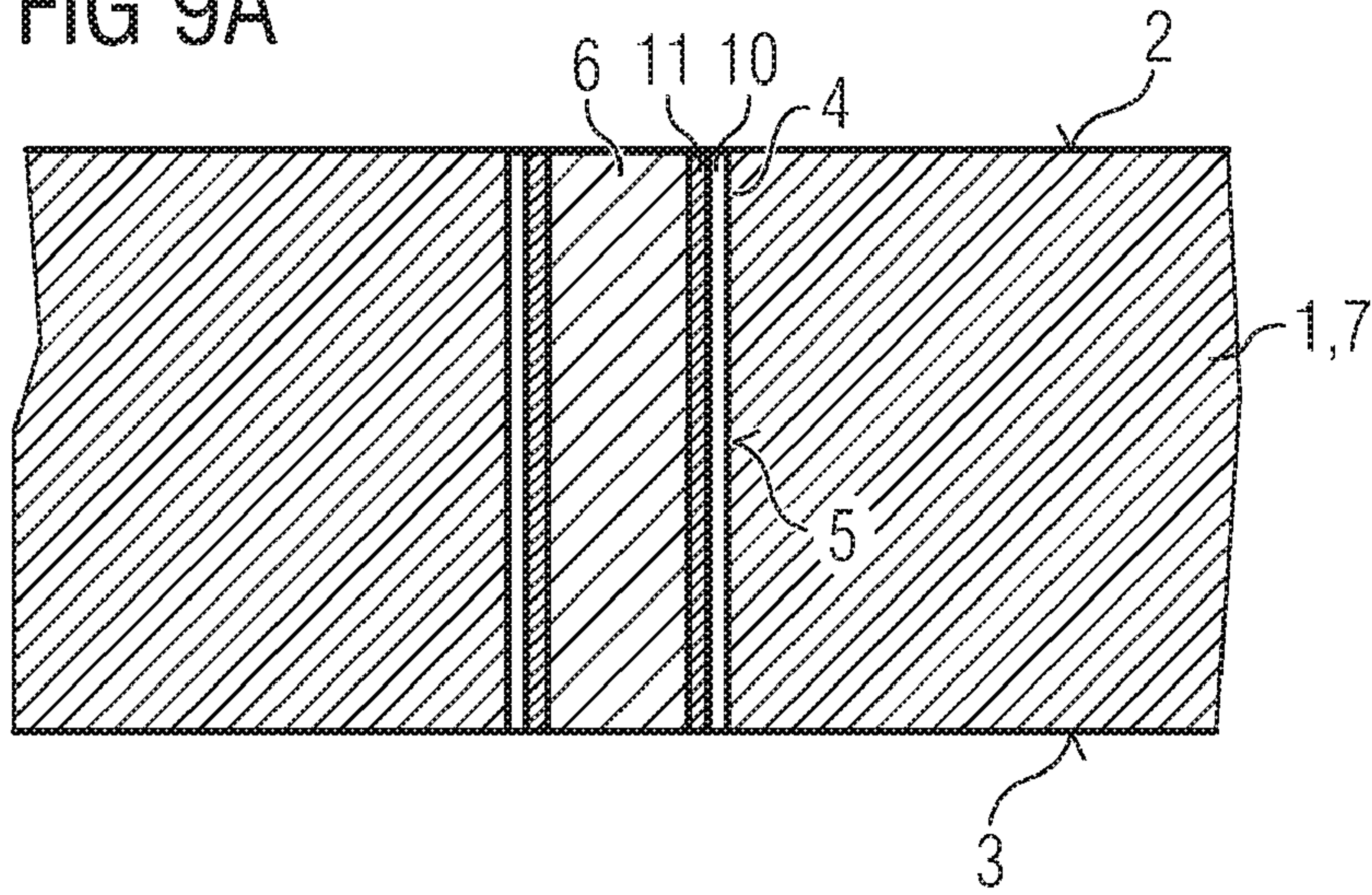


FIG 9B

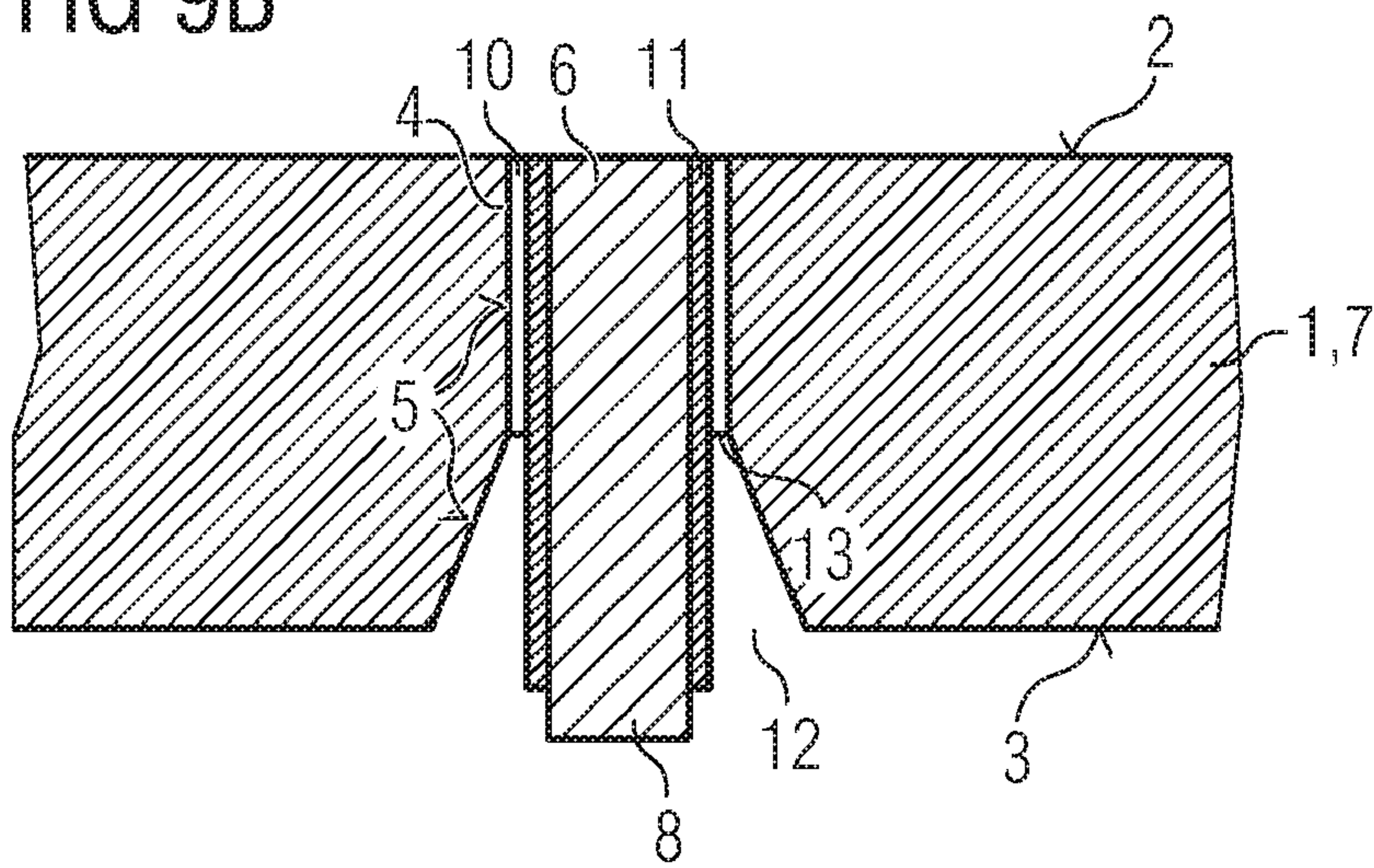
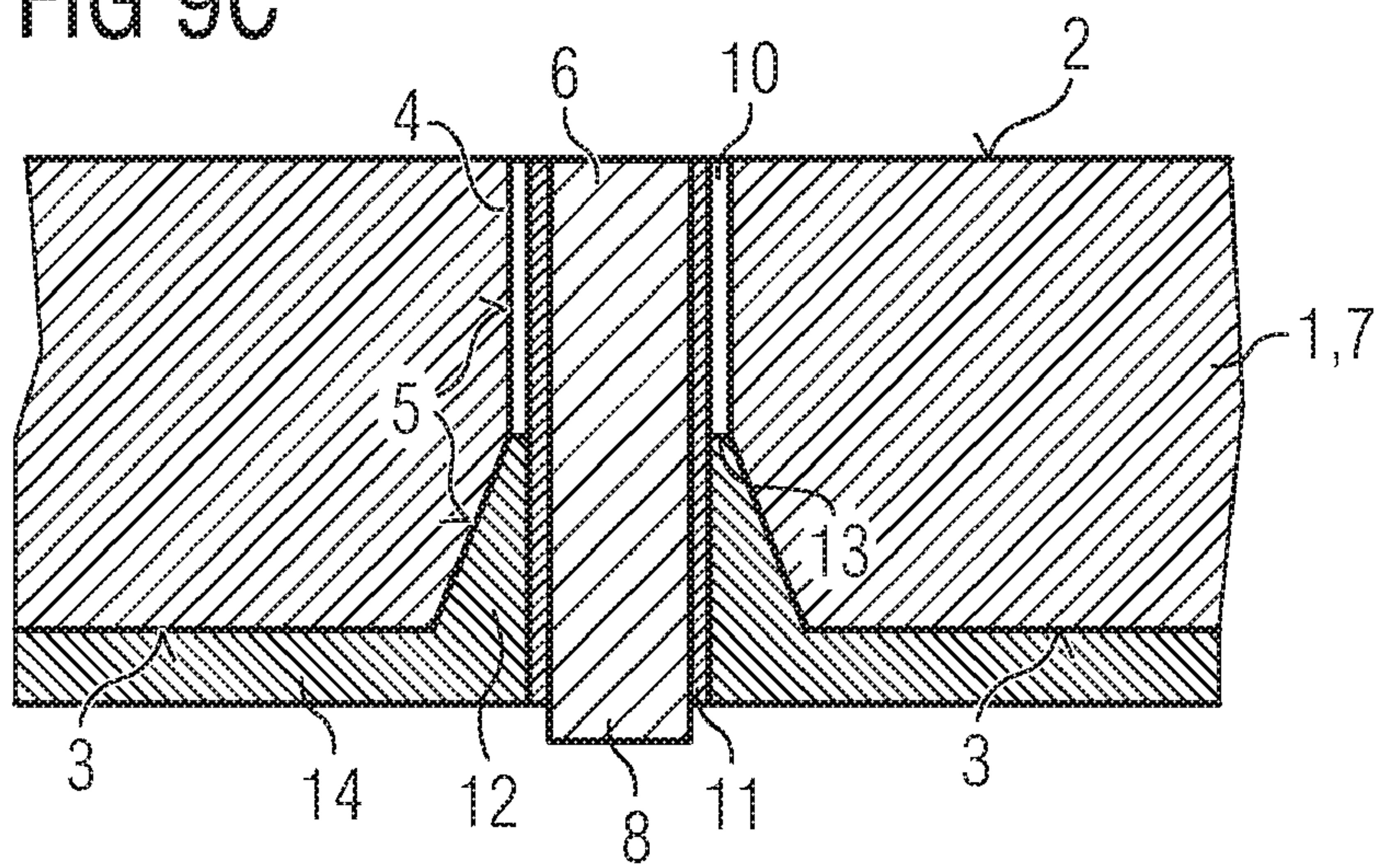


FIG 9C



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SEMICONDUCTOR DEVICE WITH AN INTERCONNECT ELEMENT AND METHOD FOR MANUFACTURE

TECHNICAL FIELD

The present method relates generally to the field of semiconductor fabrication and, more specifically, to preparing through silicon interconnects in semiconductor substrates.

BACKGROUND

To increase the functionality and density of semiconductor devices multiple semiconductor chips are stacked on a substrate or on each other. For instance, chips with the same functions, e.g., memory chips are stacked to increase the memory density or chips with different functions, e.g., processor chip and memory chip are stacked to minimize the processing time. Usually a first chip is mounted on a substrate. A second chip is then mounted onto the upper side of the first chip.

In the so called Through Silicon Interconnect Technology (TSV—Through Silicon Via), electric connections between chips, or between substrate and chip are led directly through the chip. At this, via holes are formed directly into the semiconductor substrate. The inner surface of the via holes is passivated and the via hole are filled with conductive material.

For stacking at chip level or at wafer level, the chips or the wafers each having a plurality of semiconductor chips are stacked on each other. Chips and wafers are prepared using any conventional semiconductor manufacturing process. Each semiconductor chip is provided with a plurality of interconnect elements mostly comprising a through electrode and a bump wherein a bump is formed on at least one end surface of the through electrodes.

A plurality of such chips or wafers are then sequentially stacked so that the corresponding through electrodes or bumps of adjacent chips are aligned and brought into contact so as to provide electric connection between vertical adjacent chips. In stacking at wafer level, the stacked wafers are then divided into individual chip stack packages.

SUMMARY OF THE INVENTION

A semiconductor device is configured to be electrically connected to another device by through silicon interconnect technology. The semiconductor device includes a semiconductor substrate with at least one through hole extending from an upper side to a bottom side of the semiconductor substrate. A through silicon conductor extends inside the through hole from the upper side to the bottom side of the semiconductor substrate. The through silicon conductor is electrically isolated from the semiconductor substrate and comprises a conductor bump at one of its ends. Between the inner surface of the through hole and the through silicon conductor a gap is formed. The gap surrounds the through silicon conductor on one side of the semiconductor substrate having the conductor bump, and extends from this side of the substrate into the substrate. The gap is filled with a flexible dielectric material.

To manufacture a device as above described, a dielectric layer is formed on the inner surface of a through hole extending in a semiconductor substrate from its upper side to its bottom side. Inside the through hole a through silicon conductor is formed. Furthermore a gap is formed into the semiconductor substrate, wherein the gap surrounds the through silicon conductor and extends from one side of the semicon-

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ductor substrate into the semiconductor substrate. The gap is filled with a flexible dielectric material.

BRIEF DESCRIPTION OF THE DRAWINGS

The present device and method will be more completely understood through the following detailed description, which should be read in conjunction with the attached drawings. In this description, like numbers refer to similar elements within various embodiments of the present invention. Within this detailed description, the claimed invention will be explained with respect to preferred embodiments. However, the skilled person will readily appreciate that the methods and systems described herein are merely exemplary and that variations can be made.

FIG. 1 illustrates a semiconductor device with a through silicon conductor and a gap surrounding the through silicon conductor;

FIG. 2 illustrates a further embodiment of a semiconductor device with a through silicon conductor and a surrounding gap;

FIG. 3 illustrates an embodiment of a semiconductor device comprising a gap that extends from the upper side to the bottom side of the semiconductor substrate;

FIG. 4 illustrates a semiconductor device with stacked semiconductor substrates attached to a supporting substrate;

FIGS. 5A to 5D illustrates some steps for forming a gap in a semiconductor device using lithography;

FIGS. 6A to 6D illustrates further embodiments of steps for forming a gap in a semiconductor device using lithography;

FIGS. 7A to 7D schematically illustrates a method for manufacturing a semiconductor device with a through silicon conductor and a gap surrounding the through silicon conductor;

FIGS. 8A to 8C schematically illustrates an embodiment of a method for manufacturing a semiconductor device with a through silicon conductor surrounded by two dielectric layers; and

FIGS. 9A to 9C schematically illustrates a further embodiment of a method for manufacturing a semiconductor device with a through silicon conductor surrounded by two dielectric layers.

DETAILED DESCRIPTION OF ILLUSTRATIVE EMBODIMENTS

The semiconductor device according to FIG. 1 comprises a semiconductor substrate 1 having a through hole 4. Furthermore, a through silicon conductor 6 is arranged inside the through hole 4. The through silicon conductor 6 extends from the upper side 2 to the bottom side 3 of the semiconductor substrate 1 and beyond that.

Semiconductor substrates are referred to as diverse substrates that can be integrated into a stack of semiconductor devices, e.g., silicon chips or semiconductor interposer, which can serve the connecting and holding of components in a stack. The sides of the semiconductor substrate will be referred to as upper and bottom side of the semiconductor substrate in the following also identified as upper and bottom according to its illustration in FIGS. 1 to 9. It is understood that the semiconductor substrate can be used when being rotated at 180°. The latter applies to any of the possible embodiments described below irrespective of its construction varying at the upper and bottom side of the semiconductor substrate as in for instance FIGS. 1, 2 and 4, or of a matching construction as in FIG. 3.

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The part of the through silicon conductor **6** extending beyond the bottom side **3** of the semiconductor substrate **1** forms a conductor bump **8**, that can be used to connect the semiconductor device to another device (not shown). The conductor bump can be also covered by a contact pad (not shown), which may have a larger size than the contact bump. This connection of the semiconductor device according to FIG. **1** can be carried out by use of a PCB or a laminate substrate. Also, through silicon interconnections within a stack of semiconductor substrates can be designed according to FIG. **1**.

The through silicon conductor **6** inside the semiconductor substrate **1** is completely surrounded by dielectrical material and is in this way electrically insulated from the semiconductor substrate **1**. The insulation is realized by a dielectric layer **10** surrounding the through silicon conductor **6** at an upper part of the through hole **4** adjacent to the upper side **2** of the semiconductor substrate **1**. At a lower part of the through hole **4** adjacent to the bottom side **3** of the semiconductor substrate **1**, the insulation is carried out by a dielectric flexible material **14** filling a gap **12**.

The dielectric layer **10** can include diverse materials provided that these materials with respect to their thickness provide the required electrical isolation and capacitive signal decoupling between the through silicon conductor **6** and the semiconductor bulk **7**. For instance, the dielectric layer **10** can be an oxide of the semiconductor deposited by passivation of the semiconductor. Further, nitride of the semiconductor, polymers or the like can be used.

Adjacent to the dielectric layer **10** is the dielectric flexible material **14** embedding the through silicon conductor **6** at its lower part. The shape and thickness of the dielectric flexible material **14** is determined by the gap **12**. Taking the perspective from the bottom side **3** inside the semiconductor substrate **1**, the gap **12** has a tapered form in the present embodiment. Different forms of the gap **12** are possible depending on the process of manufacturing of the gap and on the thickness of the dielectric flexible material **14** to be manufactured. The thickness of the dielectric flexible material **14** can be manufactured in a larger manner through the filling of the gap **12** compared to the thickness of the dielectric layer **10**. The mean width of the gap **12** in an embodiment is bigger than the thickness of the dielectric layer. The increased thickness enables a decrease/decline of the capacitive signal coupled between the through silicon conductor **6** and the semiconductor substrate **1**. This effect can be selectively adjusted to the point by the choice of the dielectric material and the shape of the gap **12**. Diverse low-k dielectric can be used as the dielectric flexible material **14**. For instance, polymers with permittivity within a range of 2.5 can be used and can bring an additional decoupling effect in comparison to a thin oxide layer.

By means of a thicker flexible dielectric embedding the through silicon conductor **6**, a compliant and flexible interconnect element is provided. This interconnect element can be attached to a PCB or a laminate substrate, whose coefficient of thermal expansion (CTE) deviates from the CTE of the semiconductor substrate, and thus, can compensate any possible thermo-mechanical stress. By using polymer with a high elasticity, i.e., with a low Young's modulus, there is a certain compliance of this end of the through silicon conductor **6** which enables the interconnection in a stack. The compliance is referred to as an external shear force affecting the connection between the through silicon conductor **6** and a further component (not shown). In the case of assembling the interconnect of the described semiconductor device to a non-

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CTE adapted material, the through silicon conductor **6** can be elastically deformed thereby preventing a fatigue and mechanical failure.

In one embodiment, at least the bottom side **3** of the semiconductor substrate **1** is covered by a layer of a dielectric, e.g., a layer of the dielectric flexible material. Alternatively, other suitable dielectric can be used.

FIG. **2** represents an embodiment of the semiconductor device having a gap **12** which is not completely filled. The latter design is possible depending on the performance of the semiconductor device. Also, the partial filling of the gap **12** is possible as it realizes a compliance interconnect element as well. Further alternatives for filling the gap **12** can be manufactured depending on the shape of the gap **12**.

In FIG. **3**, another embodiment of a semiconductor device is represented having both ends of the through silicon conductor **6** carried out compliant with respect to the shear force. For this purpose, the through silicon conductor **6** is completely surrounded by a gap **12** of an even width. A suitable dielectric flexible material **14** completely and evenly fills the gap **12**, and as well covers the upper and bottom side **2**, **3** of the semiconductor substrate **1**. Also in this embodiment, the form of the gap **12** can vary from the represented form. For instance, two gaps **12** describing a suitable form can be formed into the semiconductor substrate **1** entering the substrate from the upper side **2** and from the bottom side **3** so that both gaps **12** adjoin inside the semiconductor substrate **1** and that the thickness of the gap **12** and thus, of the dielectric flexible material **14** are uneven along the through silicon conductor **6**.

In contrast to FIG. **1** and FIG. **2**, the dielectric flexible material **14** in FIG. **3** forms the electric insulation of the through silicon conductor **6** over its entire length. A dielectric layer **10** is not required for the capacitive decoupling between through silicon conductor **6** and semiconductor bulk **7** but can be optional. For instance, a passivation layer (not shown) formed spontaneously under normal conditions of pH and oxygen or nitrogen concentration can cover the inner surface **5** of the through hole **4**.

FIG. **4** represents a semiconductor device which comprises two stacked semiconductor substrates **1** mounted onto a supporting substrate **17**. The supporting substrate **17** serves the connecting and holding of the stack. The supporting substrate **17** is illustrative of a general type of substrate whose structure does not constitute part of the invention. In general, the supporting substrate **17** is formed of a material which normally has a coefficient of thermal expansion that differs from the coefficient of the semiconductor substrate **1**.

The upper semiconductor substrate **15** comprises a redistribution layer **22** on its upper side **2** connected electrically to a through silicon conductor **6**. The through silicon conductor **6** extends in a through hole **4** in the upper semiconductor substrate **15** from the redistribution layer **22** through the upper semiconductor substrate **15** to its bottom side **3** and beyond it. The through silicon conductor **6** inside the through hole **4** is surrounded by a dielectric layer described above.

The part of the through silicon conductor **6** extending beyond the bottom side **3** of the semiconductor substrate **1** forms a conductor bump **8** serving to connect the through silicon conductor **6** of the upper semiconductor substrate **15** with a through silicon conductor **6** of the lower semiconductor substrate **16**, e.g., via a solder ball **20**. The solder ball **20** connects the conductor bump of the upper semiconductor substrate **15** with a contact pad **18** formed on a side of an interconnect element which faces the upper semiconductor substrate **15** inside the lower semiconductor substrate **16**. The

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upper semiconductor substrate **15** is electrically connected with a contact pad **18** of the supporting substrate **17** through this interconnect element.

The interconnect element of the lower semiconductor substrate **16** comprises a through silicon conductor **6** formed inside a through hole **4** that is electrically insulated from the bulk **7** of the lower semiconductor substrate **16**. The lower semiconductor substrate **16** is surrounded by a gap **12** on its bottom side **3** facing the supporting substrate **17**. The gap **12** is filled with a dielectric flexible material **14**. Further, the bottom side **3** of the lower semiconductor substrate **16** is covered by the dielectric flexible material **14**. The embodiment of the interconnect element of the lower semiconductor substrate **16** accords in the present embodiment of the semiconductor device with the one in FIG. **1**, and is described more in detail further above. It is understood that alternatively other described embodiments of the compliant interconnect elements can be formed.

In the presented embodiment, the upper semiconductor substrate **15** has no compliant interconnect element because both stacked semiconductor substrates **1** have a comparable thermal expansion behavior. As a matter of course, both semiconductor substrates **1** can have compliant interconnect elements which are formed either comparable or differing from each other irrespective of the substrates' thermal expansion behavior. Likewise, more than two semiconductor substrates **1** can be stacked.

Even though in FIG. **1** to **4** only one compliant interconnect element is presented, it is understood that more than one can be formed in a semiconductor substrate **1**.

FIGS. **5A** to **5D** and FIGS. **6A** to **6D** illustrate some steps of manufacturing and filling of the gap **12** having diverse forms. A through silicon conductor **6** is arranged in a through hole **4** of a semiconductor substrate **1** and is surrounded by a dielectric layer **10** (FIG. **5A**, FIG. **6A**). A mask **19** is formed on the bottom side **3** of the semiconductor substrate **1** to define the structure of the gap **12** surrounding the through silicon conductor **6**. It is understood that the structure of a wide range of gaps **12** can be defined by means of the mask. Alternatively or complementary, the mask **19** can be formed on the upper side **2** for the manufacturing of a gap **12** on this side of the semiconductor substrate **1**. The manufacturing of the mask **19** is carried out by one of the known processes, e.g., by lithography.

Forming the gap **12** into the semiconductor substrate **1** can be done e.g. by an isotropic or anisotropic etch process. Diverse wet etching processes (e.g., FIG. **5B**) or dry etching processes known are suitable. A roughly cylindrical form of a gap **12** with a well adjustable depth (FIG. **6B**) can be produced by, e.g., Deep Reactive Ion Etching (DRIE) known as a so called Bosch process. After the etching process, the semiconductor substrate **1** is removed from a by the mask **19** defined area surrounding the through silicon conductor **6**. The gap **12** has a certain depth. The through silicon conductor **6** and the dielectric layer **10** embedding the through silicon conductor **6** entirely project into the gap **12** (FIG. **5B** and FIG. **6B**). The depth of the gap **12** in the represented embodiment is slightly bigger than half of the thickness of the semiconductor substrate **1**. A larger or smaller depth can also be chosen depending on the form of the gap **12** and the expected lateral deformation of the through silicon conductor **6**.

In a subsequent step, the gap **12** is filled with a dielectric flexible material **14**, e.g., a suitable polymer so that the dielectric flexible material **14** embeds the uncovered end of the through silicon conductor **6** (FIG. **5C** and FIG. **6D**). There are different ways to fill the gap **12**. In one way, the dielectric flexible material **14** is filled into the gap **12** by a spin or a spray

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or a print process or the like. Subsequently, the mask **19** is stripped off (FIG. **5C**). In a next step, a dielectric layer can be deposited onto the bottom side **3** of the semiconductor substrate **1** (not shown) also covering the surface of the gap **12**.

Another way could be filling the gap **12** after stripping the mask. The filling process of the dielectric flexible material **14** can be executed with or without a structure definition for the filling by, e.g., lithography or the like. Furthermore, it can comprise a deposition of a layer of the dielectric flexible material **14** covering the bottom side **3** of the semiconductor substrate **1** (FIG. **6D**).

For forming a conductor bump **8**, the upper side and the dielectric flexible material **14** and the dielectric layer **10** are planar etched so that a part of the through silicon conductor **6** extends out of the etched surface and which forms the conductor bump **8** (FIG. **5D**). In an alternative embodiment, a planar etch process for forming a conductor bump **8** can be executed before filling the gap **12** (FIG. **6C**) either simultaneously or separate from forming the gap **12**.

A starting point for another embodiment of the method for manufacturing a semiconductor device with an interconnect element is again a semiconductor substrate **1** with a through hole **4** (FIG. **7A**). The inner surface **5** of the through hole **4** is covered by a dielectric layer **10**, e.g., a silicon passivation using silicon oxide or silicon nitride. Inside the through hole **4** adjoining the dielectric layer **10**, a pillar shaped through silicon conductor **6** is arranged. Different ways are known for forming the through silicon conductor **6** depending on the material used for forming the same. Materials such as copper, polysilicon, conductive paste, solder or the like can be used for the through silicon conductor **6**. In an embodiment, a seed layer, e.g., a copper-seed layer is deposited on the dielectric layer **10** for depositing the through silicon conductor **6** made of copper inside the through hole **4**.

By use of RIE (Reactive Ion Etching), a planar etching back of the bottom side **3** of the semiconductor substrate **1**, and simultaneously an isotropic etching of the semiconductor substrate **1** and the dielectric layer **10** occurs along the through silicon conductor **6** for forming the gap **12**. Subsequently to the etch process, a planar bottom side **3** of the semiconductor substrate **1** and a tapered gap **12** are formed running along the through silicon conductor **6** into the semiconductor substrate **1** (FIG. **7B**). According to the illustrated embodiment, its depth is approximately half the thickness of the semiconductor substrate **1** after the etching. Its mean width is larger than the thickness of the dielectric layer **10**. Also, such an etch process is self aligned and does not require a lithography process. Due to the recess etch of the planar bottom side **3**, the through silicon conductor **6** protrudes the surface of the semiconductor substrate **1**.

With then depositing a dielectric flexible material **14** by, e.g., spin coating, the gap **12** is completely filled and at the same time the bottom side **3** of the semiconductor substrate **1** as well as the through silicon conductor **6** is evenly covered with a layer (FIG. **7C**). For filling the gap **12** and manufacturing the planar layer, other processes are possible such as a printing process or a CVD process provided that a planar layer is producible by the chosen process and that also the gap **12** is filled evenly according to FIG. **7C**. The deposition of the layer by this process from, e.g., a polymer, is self aligned with respect to the planarity of the layer. Subsequently, a conductor bump **8** is formed by a further isotropic etching of the dielectric flexible material **14** until a part of the through silicon conductor **6** is uncovered (FIG. **7D**).

In further embodiments, the method for manufacturing the gap **12** is modified in a way that the width of the gap **12** can be selectively adjusted to the point in a self aligned etch process.

And it is for this purpose that the through silicon conductor **6** inside the semiconductor substrate **1** is embedded by two layers, a dielectric layer **10** as described above (hereinafter referred to as first dielectric layer **10**) and a second dielectric layer **11**. The second dielectric layer **11** just like the first dielectric layer **10** can be used for capacitive signal decoupling between the through silicon conductor **6** and the semiconductor bulk **7**, because of its dielectric characteristics. At the same time, the second dielectric layer serves as a sacrificial layer for adjusting the width of the gap **12**. Hereinafter, the layer covering the inner surface **5** of the semiconductor through hole **4** should be referred to as first dielectric layer **11**. And the layer arranged between the first dielectric layer **10** and the through silicon conductor **6** should be referred to as second dielectric layer **11**.

FIG. **8A** to FIG. **8C** illustrate schematically several steps to manufacture a semiconductor device with an interconnect element which has inwards-looking at first a first dielectric layer **10** then a second dielectric layer **11** also used as a sacrificial layer and at last, in the middle, a through silicon conductor **6** inside the through hole **4** (FIG. **8A**). The second dielectric layer **11** as well as the first dielectric layer **10** can consist of diverse materials. Suitable materials are any dielectric materials with an etching rate higher than the etching rate of the first dielectric layer **10**. In this way, the above described tapered form of the gap **12** can be manufactured in a self aligning manner although using two dielectric layers **10**, **11**.

With this, a planar etch back process as described above occurs. Subsequent to the etch process, the base area **13** of the gap **12** adjoins the second dielectric layer **11** according to this embodiment. Because of the above described selective etching behavior, the width of the base area **13** is as big as the thickness of the second dielectric layer **11**, so that the width of the gap **12** can be adjusted through the thickness of the second dielectric layer **11**. The first dielectric layer **10** within the area of the gap **12** is removed through a suitable choice of materials of the first dielectric layer **10** as, e.g., a passivation layer of the semiconductor substrate **1**. Therefore, only the through silicon conductor **6** projects into the gap **12** (FIG. **8B**).

Following, as per FIG. **7B** and FIG. **7C** the gap **12** is filled with a dielectric flexible material **14**, the semiconductor substrate **1** is covered by the dielectric flexible material **14** and a conductor bump **8** is formed on the side of the semiconductor substrate **1** where the gap **12** is arranged as well. It can be referred to the above descriptions for these steps of the process.

FIG. **9A** to FIG. **9C** shows another embodiment for manufacturing an interconnect element in a semiconductor substrate **1** by use of a sacrificial dielectric layer. This embodiment can be distinguished from the one of FIGS. **8A** to **8C** as the first dielectric layer **10** serves as a sacrificial layer here. By the way, the initial state of the semiconductor substrate **1** before forming the gap **12** is comparable to the above described on (FIG. **9A**).

For manufacturing a gap **12** having a suitable form, the first dielectric layer **10** consists of such a material whose etching rate is higher than the etching rate of the semiconductor.

Furthermore, the second dielectric layer **11** is made of a material which is in comparison to the first dielectric layer **10** etched only a little while the gap **12** is formed. Thus, the second dielectric layer **11** almost entirely embeds the through silicon conductor **6** after the etching process. Solely, a small part of the through silicon conductor **6** is laid open. This forms the conductor bump **8**. As already described further above, in this process the width of the gap **12** is adjusted through the thickness of the sacrificial layer, though in this case, it is through the thickness of the first dielectric layer **10**. For filling the gap **12** and depositing the planar layer for insulating the semiconductor substrate **1** (FIG. **9C**), it is referred to the above descriptions.

What is claimed is:

1. A semiconductor device configured to be electrically connected to another device by through silicon interconnect technology, the semiconductor device comprising:

a semiconductor substrate with at least one through hole extending from a first surface to a second surface of the semiconductor substrate;

a through silicon conductor extending inside the through hole from the first surface to the second surface of the semiconductor substrate, wherein the through silicon conductor is electrically isolated from the semiconductor substrate;

a conductor bump electrically connected to an end of the through silicon conductor adjacent the first surface; and

a gap between the semiconductor substrate and the through silicon conductor, the gap surrounding the through silicon conductor adjacent the first surface of the semiconductor substrate, the gap extending from the first surface into the semiconductor substrate and a flexible dielectric material at least partially filling the gap,

wherein a length of the gap into the semiconductor substrate is smaller than a thickness of the semiconductor substrate.

2. The semiconductor device of claim **1**, wherein the flexible dielectric material isolates the through silicon conductor from the semiconductor substrate within the area of the gap.

3. The semiconductor device of claim **1**, further comprising a dielectric layer between the through silicon conductor and the semiconductor substrate.

4. The semiconductor device of claim **3**, further comprising a second dielectric layer that partially surrounds the through silicon conductor, wherein the gap adjoins to the second dielectric layer.

5. The semiconductor device of claim **1**, wherein the flexible dielectric material only partially fills the gap.

6. The semiconductor device of claim **1**, wherein the flexible dielectric material covers the first surface of the semiconductor substrate.

7. The semiconductor device according to claim **1**, wherein the flexible dielectric material is a polymer flexible dielectric material.